=> file registry
FILE 'REGISTRY' ENTERED AT 16:12:15 ON 26 APR 2006
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.
PLEASE SEE "HELP USAGETERMS" FOR DETAILS.
COPYRIGHT (C) 2006 American Chemical Society (ACS)

Property values tagged with IC are from the ZIC/VINITI data file provided by InfoChem.

STRUCTURE FILE UPDATES: 25 APR 2006 HIGHEST RN 881879-55-6 DICTIONARY FILE UPDATES: 25 APR 2006 HIGHEST RN 881879-55-6

New CAS Information Use Policies, enter HELP USAGETERMS for details.

TSCA INFORMATION NOW CURRENT THROUGH January 6, 2006

Please note that search-term pricing does apply when conducting SmartSELECT searches.

Structure search iteration limits have been increased. See HELP SLIMITS for details.

REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

http://www.cas.org/ONLINE/UG/regprops.html

=> d ide L3

```
L3
     ANSWER 1 OF 1 REGISTRY COPYRIGHT 2006 ACS on STN
     7440-21-3 REGISTRY
RΝ
     Entered STN: 16 Nov 1984
     Silicon (7CI, 8CI, 9CI) (CA INDEX NAME)
OTHER NAMES:
     CZ-N Polished wafer
     GKO 3516A
CN
CN
     Hexsil
CN
     HGH 600
CN
     KDB 10
CN
     KDB 20
CN
     KR 1
CN
     Metasilicon 325A
CN
     Polysilicon
CN
     SI 1059
CN
     Sicomill 4C-P
CN
     Sicomill Grade 2
     SIE 17PB
CN
CN
     Silgrain Standard
CN
     Silicon element
```

```
CN
     SILSO
     17375-03-0, 72516-01-9, 72516-02-0, 72516-03-1, 71536-23-7, 152284-21-4,
DR
     90337-93-2, 157383-37-4, 160371-18-6
MF
     Si
CI
LC
     STN Files:
                  ADISNEWS, AGRICOLA, ANABSTR, BIOSIS, BIOTECHNO, CA, CABA,
       CAOLD, CAPLUS, CASREACT, CBNB, CHEMCATS, CHEMINFORMRX, CHEMLIST, CIN,
       CSCHEM, CSNB, DDFU, DETHERM*, DIOGENES, DIPPR*, DRUGU, EMBASE,
       ENCOMPLIT, ENCOMPLIT2, ENCOMPPAT, ENCOMPPAT2, HSDB*, IFICDB, IFIPAT,
       IFIUDB, IPA, MEDLINE, MRCK*, MSDS-OHS, NIOSHTIC, PDLCOM*, PIRA, PROMT,
       RTECS*, TOXCENTER, TULSA, ULIDAT, USPAT2, USPATFULL, VTB
         (*File contains numerically searchable property data)
     Other Sources: DSL**, EINECS**, TSCA**
         (**Enter CHEMLIST File for up-to-date regulatory information)
```

Si

### \*\*PROPERTY DATA AVAILABLE IN THE 'PROP' FORMAT\*\*

436311 REFERENCES IN FILE CA (1907 TO DATE)
8914 REFERENCES TO NON-SPECIFIC DERIVATIVES IN FILE CA
436939 REFERENCES IN FILE CAPLUS (1907 TO DATE)
1 REFERENCES IN FILE CAOLD (PRIOR TO 1967)

=> => file casreact FILE 'CASREACT' ENTERED AT 17:48:30 ON 27 APR 2006 USE IS SUBJECT TO THE TERMS OF YOUR CUSTOMER AGREEMENT COPYRIGHT (C) 2006 AMERICAN CHEMICAL SOCIETY (ACS)

Copyright of the articles to which records in this database refer is held by the publishers listed in the PUBLISHER (PB) field (available for records published or updated in Chemical Abstracts after December 26, 1996), unless otherwise indicated in the original publications.

FILE CONTENT: 1840 - 23 Apr 2006 VOL 144 ISS 17

New CAS Information Use Policies, enter HELP USAGETERMS for details.

Some CASREACT records are derived from the ZIC/VINITI database (1974-1991) provided by InfoChem, INPI data prior to 1986, and Biotransformations database compiled under the direction of Professor Dr. Klaus Kieslich.

This file contains CAS Registry Numbers for easy and accurate substance identification.

```
=> d stat que L23
         164220 SEA FILE=REGISTRY ABB=ON PLU=ON SI>O AND (F>O OR CL>O OR
L10
               BR>0)
          63332 SEA FILE=REGISTRY ABB=ON PLU=ON SI>O AND F>0
L11
          42881 SEA FILE=REGISTRY ABB=ON
                                         PLU=ON L10 AND CASREACT/LC
L13
          13948 SEA FILE=REGISTRY ABB=ON PLU=ON L13 AND L11
L14
          28933 SEA FILE=REGISTRY ABB=ON PLU=ON L13 NOT L14
L15
            88 SEA FILE=CASREACT ABB=ON PLU=ON 7440-21-3/RRT
L19
          10750 SEA FILE=CASREACT ABB=ON PLU=ON L15/PRO
L21
            46 SEA FILE=CASREACT ABB=ON PLU=ON L19 (L) L21
L23
```

=> s L22 or L23 L74 46 L22 OR L23

=> file caplus FILE 'CAPLUS' ENTERED AT 17:49:33 ON 27 APR 2006 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS. COPYRIGHT (C) 2006 AMERICAN CHEMICAL SOCIETY (ACS)

Copyright of the articles to which records in this database refer is held by the publishers listed in the PUBLISHER (PB) field (available for records published or updated in Chemical Abstracts after December 26, 1996), unless otherwise indicated in the original publications. The CA Lexicon is the copyrighted intellectual property of the American Chemical Society and is provided to assist you in searching databases on STN. Any dissemination, distribution, copying, or storing of this information, without the prior written consent of CAS, is strictly prohibited.

FILE COVERS 1907 - 27 Apr 2006 VOL 144 ISS 18 FILE LAST UPDATED: 26 Apr 2006 (20060426/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply. They are available for your review at:

http://www.cas.org/infopolicy.html
'OBI' IS DEFAULT SEARCH FIELD FOR 'CAPLUS' FILE

```
=> d stat que L27
L2
             1 SEA FILE=REGISTRY ABB=ON PLU=ON SILICON/CN
L10
         164220 SEA FILE=REGISTRY ABB=ON PLU=ON SI>O AND (F>O OR CL>O OR
               BR>0)
         17965 SEA FILE=CAPLUS ABB=ON PLU=ON L2 (L) (RGT OR RCT OR RACT)/RL
L16
L17
         53505 SEA FILE=CAPLUS ABB=ON PLU=ON L10/PREP
           462 SEA FILE=CAPLUS ABB=ON PLU=ON L16 AND L17
L18
L24
         110513 SEA FILE=CAPLUS ABB=ON PLU=ON
                                               ?MICROWAV?/BI
            35 SEA FILE=CAPLUS ABB=ON PLU=ON
                                               M/OBI(1W)WAVE/BI
L25
             5 SEA FILE=CAPLUS ABB=ON PLU=ON L18 AND (L24 OR L25)
L27
```

```
=> d stat que L63
L3 STR
```

Si 1

NODE ATTRIBUTES: DEFAULT MLEVEL IS ATOM DEFAULT ECLEVEL IS LIMITED

GRAPH ATTRIBUTES:

RING(S) ARE ISOLATED OR EMBEDDED

NUMBER OF NODES IS

```
STEREO ATTRIBUTES: NONE
```

L4	395584	SEA FILE=REGISTRY FAM FUL L3
L10	164220	SEA FILE=REGISTRY ABB=ON PLU=ON SI>O AND (F>O OR CL>O OR
		BR>0)
L17	53505	SEA FILE=CAPLUS ABB=ON PLU=ON L10/PREP
L24	110513	SEA FILE=CAPLUS ABB=ON PLU=ON ?MICROWAV?/BI
L25		SEA FILE=CAPLUS ABB=ON PLU=ON M/OBI(1W)WAVE/BI
L55		SEA FILE=REGISTRY ABB=ON PLU=ON L4 AND CAPLUS/LC
L59	369838	SEA FILE=REGISTRY ABB=ON PLU=ON L55 AND AYS/CI
L60	24334	SEA FILE=REGISTRY ABB=ON PLU=ON L55 NOT L59
L61	28637	SEA FILE=CAPLUS ABB=ON PLU=ON L60 (L) (RGT OR RCT OR
		RACT)/RL
L62	665	SEA FILE=CAPLUS ABB=ON PLU=ON L61 AND L17
L63	7	SEA FILE=CAPLUS ABB=ON PLU=ON L62 AND (L24 OR L25)

=> s L27 or L63

L75 7 L27 OR L63

=> d ibib abs hit L74 1-46; d ibib abs hitind hitstr L75 1-7
YOU HAVE REQUESTED DATA FROM FILE 'CASREACT' - CONTINUE? (Y)/N:v

L74 ANSWER 1 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 142:482091 CASREACT

TITLE: Direct Reaction of Silicon with  $\alpha$ - $\omega$  Dichloroalkanes: Direct Formation of

Dichlorosilacyclopentane

AUTHOR(S): Lewis, Larry N.; Whitney, John M.; Bui, Pierre

CORPORATE SOURCE: GE Global Research Center, Niskayuna, NY, 12309, USA

SOURCE: Organometallics (2005), 24(9), 2141-2146

CODEN: ORGND7; ISSN: 0276-7333

PUBLISHER: American Chemical Society

DOCUMENT TYPE: Journal LANGUAGE: English

AB The direct reaction of Si with 1,4-dichlorobutane in the presence of a CuCl catalyst gives high selectivity for dichlorosilacyclopentane under some conditions. The effects of residence time, temperature, and promoters are explored, and the highest selectivity occurs at short residence time and in the presence of a Cd promoter. The reaction of Si with Me chloride is discussed as well. The Me chloride reaction is usually promoted by Zn and not by Cd. The reaction of Si with 1,3-dichloropropane and with 1,5-dichloropentane was also explored; however poor selectivity to any product occurred with these other dichloroalkanes. The origin of the selectivity for the silacyclopentane is discussed in terms of low

activation energy for ring closure in the five-membered ring case. Other low activation options such as reaction of silylene intermediate with C-H vs. C-Cl prevent good selectivity in the dichloropropane and dichloropentane reactions.

REFERENCE COUNT:

THERE ARE 23 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 3 A ===> B

RGT C 7440-21-3 Si

PRO B 2406-33-9

CAT 7758-89-6 CuCl, 7440-43-9 Cd, 7440-31-5 Sn

CON 300 deg C

NTE fixed bed reactor, gas phase, no solvent, thermal, Cd promoter gave better results than Zn

RX(2) OF 3 G ===> H

$$C1$$
 $C1$ 
 $C1$ 
 $C1$ 
 $C1$ 
 $C1$ 
 $C2$ 

Н

RGT C 7440-21-3 Si

PRO H 2351-33-9

CAT 7758-89-6 CuCl, 7440-43-9 Cd, 7440-31-5 Sn

CON 300 deg C

NTE fixed bed reactor, gas phase, no solvent, thermal, poor product selectivity, 50% conversion, 15% selectivity

RX(3) OF 3 I ===>  $\mathbf{J}$ 

$$c1$$
 $(CH_2)$ 
 $3$ 
 $c1$ 
 $(CH_2)$ 
 $3$ 
 $3$ 
 $3$ 
 $4$ 
 $5$ 
 $1$ 
 $3$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $5$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 
 $4$ 
 $1$ 

RX(3) RCT I 628-76-2

RGT C 7440-21-3 Si

PRO J 2406-34-0

CAT 7758-89-6 CuCl, 7440-43-9 Cd, 7440-31-5 Sn

CON 300 deg C

NTE fixed bed reactor, gas phase, no solvent, thermal, poor product selectivity, trace yield

L74 ANSWER 2 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 142:219410 CASREACT

TITLE: Preparation of organohalosilanes

INVENTOR(S): Aramata, Mikio; Ishizaka, Hajime; Inukai, Tetsuya

PATENT ASSIGNEE(S): Shin-Etsu Chemical Co., Ltd., Japan

SOURCE: Eur. Pat. Appl., 15 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND DATE	APPLICATION NO.	DATE
EP 1508571	A1 2005022	EP 2004-254984	20040819
R: AT, BE,	CH, DE, DK, ES	S, FR, GB, GR, IT, LI, LU	J, NL, SE, MC, PT,
		O, MK, CY, AL, TR, BG, C	
JP 2005097249	A2 2005041	L4 JP 2004-179538	20040617
US 2005043557	A1 2005022	US 2004-919072	20040816
PRIORITY APPLN. INFO	.:	JP 2003-297246	20030821
		JP 2004-179538	20040617

OTHER SOURCE(S): MARPAT 142:219410

Organohalosilanes are prepared by charging a reactor with a contact mass of metallic silicon and a catalyst and feeding an organo halide-containing gas to the reactor. Tin or a tin compound is used as the catalyst. Then organohalosilanes can be produced quite efficiently at a high reaction rate while maintaining a low T/D ratio and minimizing the deposition of byproducts and carbon. Thus, tin catalyzed reaction of metallic silicon with chlorobenzene gave mainly dichlorodiphenylsilane.

REFERENCE COUNT: 1 THERE ARE 1 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 2 A ===> B

RX(1) RCT A 108-90-7 RGT C 7440-21-3 Si B 80-10-4 PRO 7440-31-5 Sn CAT CON 450 deg C

CASREACT COPYRIGHT 2006 ACS on STN L74 ANSWER 3 OF 46

ACCESSION NUMBER: 141:243682 CASREACT

Process for direct synthesis of methylchlorosilanes TITLE:

> from methyl chloride and contact mass of silicon, copper and aluminum in presence of zinc and tin,

antimony or phosphorus promoters

Endovin, Yu. P.; Baturova, S. A.; Chekrii, E. N.; Pererva, O. V.; Semenok, E. V.; Vavilov, V. V.; INVENTOR(S):

Polivanov, A. N.; Storozhenko, P. A.

FGUP Gos. Nauchno-Issled. Inst. Khim. Tekhnol. PATENT ASSIGNEE(S):

Elementoorganicheskikh Soedinenii, Russia

Russ., No pp. given CODEN: RUXXE7 SOURCE:

DOCUMENT TYPE: Patent LANGUAGE: Russian

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
RU 2232764	C1	20040720	RU 2003-101868	20030127
PRIORITY APPLIA. INFO.	:		RU 2003-101868	20030127

Methylchlorosilanes, useful as substrates for preparation of organosilicon oligomers and polymers (no data), are prepared in a direct synthesis by reaction of Me chloride with a contact mass containing powdered Si, Cu, Al and an

activating agent consisting of a mixture of Zn or its compds. and an element chosen from Sn, Sb, P or their compds. taken sep. or in different combinations at temps. <350° up to Si conversions of 2-10 weight %, followed by addnl. charging Al-free contact mass. In an example, 243.85 g powdered Si, 5.0 g powdered Cu, 0.01 g powdered Sn, 0.5 g powdered Zn and 0.63 g powdered

Al are combined at room temperature and charged to a tubular glass reactor of 30

mm diameter and 500 mm height equipped with an elec. heater along its length and a porous plate for addition of MeCl in its lower part, and this contact mass is purged with N2 for 30 min and heated to 300°, whereupon MeCl is added at a rate of 150 g/h via the porous plate; after 7 h, conversion of Si is 68.3% and the Me2SiCl2 content in the products is 90.0%, whereas after 40 h, conversion of Si is 90.0 % and the Me2SiCl2 content is 90.5%, and further reaction is carried out with a contact mass containing no Al. This process provides higher conversions of Si and greater selectivity toward Me2SiCl2 than prior art.

## RX(1) OF 1 3 A ===> B + C

RX(1) RCT A 74-87-3

RGT D 7440-21-3 Si

PRO B 75-78-5, C 75-79-6

CAT 7440-50-8 Cu, 7429-90-5 Al, 7440-66-6 Zn, 7440-31-5 Sn

CON SUBSTAGE(1) room temperature SUBSTAGE(2) 40 hours, 300 deg C

NTE other products also detected, thermal, 300°, tubular reactor, second charge of contact mass has no Al

L74 ANSWER 4 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 141:207275 CASREACT

TITLE: The direct synthesis of methylchlorosilanes: New

aspects concerning its mechanism

AUTHOR(S): Lorey, Lars; Roewer, Gerhard

CORPORATE SOURCE: Institut fuer Anorganische Chemie, TU Bergakademie

Freiberg, Freiberg, D-9596, Germany

SOURCE: Silicon Chemistry (2004), Volume Date 2002, 1(4),

299-308

CODEN: SCIHB4; ISSN: 1569-0660

PUBLISHER: Kluwer Academic Publishers

DOCUMENT TYPE: Journal LANGUAGE: English

AB New results are given regarding the mechanism of the chemical process of Cu alloyed Si with Me chloride (the 'direct process'). As indicated by Photo-EMF measurements, carried out with doped Si samples the reactivity of Si significantly depends on the type of the doping with elements like P (n-type) Sn, B or In (p-type). In-situ trapping expts. with 2,3-dimethylbutadiene are consistent with the creation of silylene intermediates SiMeCl and SiCl2. The selectivity of their competitive insertion steps can be controlled by the doping type and concns. of the doping elements, especially the P/Sn ratio criterion. N-Type doping favors the silylene insertion into the C-Cl bond due to the electronic silylene stabilization on the Si surface. In case of p-type doping silylene

insertion into Si-Cl bond is favored more intensively giving disilanes.

REFERENCE COUNT: 23 THERE ARE 23 CITED REFERENCES AVAILABLE FOR THIS

RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 2 A ===> **B** 

$$H_3C + C1$$
 $C1 C1$ 
 $C1$ 
 $C1$ 

RCT A 74-87-3 RX(1) RGT C 7440-21-3 Si PRO B 75-78-5 CAT 7440-50-8 Cu, 7723-14-0 P CON 603K, 2 bar NTE no solvent, gas-solid reaction, flow-tube reactor, other products also detected

L74 ANSWER 5 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

140:128521 CASREACT

TITLE:

Method for preparation of alkylhalosilanes

INVENTOR(S):

Lewis, Larry Neil; Crawford, Alan Carson

PATENT ASSIGNEE(S):

General Electric Company, USA U.S. Pat. Appl. Publ., 8 pp.

SOURCE:

CODEN: USXXCO

DOCUMENT TYPE: LANGUAGE:

Patent English

11

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

	PAT	ENT I	NO.		KI	ND :	DATE			A)	PPLI	CATIO	ои ис	ο.	DATE			
										_								
	US	2004	0242	35	A	1	2004	0205		U:	5 20	02-2	07342	2	2002	0730		
•	US	6717	004		B	2	2004	0406										
1	WO	2005	0829	13	A	1	2005	0909		W	20	03-U	52393	20	2003	0731		
		<b>W</b> :	ΑE,	AG,	AL,	AM,	ΑT,	AU,	ΑZ,	BA,	BB,	BG,	BR,	BY,	ΒZ,	CA,	CH,	CN,
			CO,	CR,	CU,	CZ,	DE,	DK,	DM,	DZ,	EC,	EE,	ES,	FI,	GB,	GD,	GE,	GH,
			GM,	HR,	HU,	ID,	IL,	IN,	IS,	JP,	KE,	KG,	KP,	KR,	ΚZ,	LC,	LK,	LR,
			LS,	LT,	LU,	LV,	MA,	MD,	MG,	MK,	MN,	MW,	MX,	ΜZ,	NO,	ΝZ,	OM,	PH,
			PL,	PT,	RO,	RU,	SD,	SE,	SG,	SK,	SL,	ТJ,	TM,	TN,	TR,	TT,	TZ,	UA,
			UG,	UZ,	VN,	YU,	ZA,	ZM,	ZW									
		RW:	GH,	GM,	ΚE,	LS,	MW,	MZ,	SD,	SL,	SZ,	TZ,	UG,	ZM,	ZW,	AM,	ΑZ,	BY,
			KG,	ΚZ,	MD,	RU,	ТJ,	TM,	ΑT,	BE,	BG,	CH,	CY,	CZ,	DE,	DK,	EE,	ES,
			FI,	FR,	GB,	GR,	HU,	ΙE,	IT,	LU,	MC,	NL,	PT,	RO,	SE,	SI,	SK,	TR,
			BF,	ВJ,	CF,	CG,	CI,	CM,	GΑ,	GN,	GQ,	GW,	ML,	MR,	ΝE,	SN,	TD,	TG
	AU	2003	2570	58	A	1	2005	0914		ΑI	J 20	03-2	5705	8	2003	0731		
PRIOR	ITY	APP	LN.	INFO	. :					U	3 20	02-2	07342	2	2002	0730		
										W	20	03-U	S2392	20	2003	0731		
	_						~ -						-					

A method for making alkylhalosilanes is provided comprising reacting an AΒ alkyl halide and silicon in the presence of a copper catalyst comprising copper powder, particulated copper, copper flake, or combinations thereof and at least one co-catalyst.

REFERENCE COUNT:

THERE ARE 11 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 2 A ===> B H3C<sup>★</sup>Cl 2 A В

RX (1)

STAGE(1)

RGT C 7440-21-3 Si

CAT 7440-66-6 Zn, 7440-50-8 Cu

CON SUBSTAGE(1) 0.5 hours, room temperature SUBSTAGE(2) 0.5 hours, room temperature -> 310 deg C

STAGE(2)

RCT A 74-87-3 CON 310 deg C

PRO B **75-78-5** 

NTE gas phase, fixed-bed reactor used, either copper flake catalyst or copper OMG 831 powder catalyst can be used

L74 ANSWER 6 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

139:381608 CASREACT

TITLE:

SOURCE:

Method for preparing a contact mass of copper-silicon

for production of alkylhalosilane

INVENTOR(S):

Lewis, Larry Neil; Buckley, Paul William; Bablin, John

Mathew; Wilson, Paul Russell; Smith, David John

PATENT ASSIGNEE(S):

General Electric Company, USA U.S. Pat. Appl. Publ., 6 pp.

CODEN: USXXCO

DOCUMENT TYPE:

Patent

LANGUAGE:

English

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND DATE	DATE APPLICATION NO. DATE					
US 2003220514	A1 20031127	20031127 US 2002-150829 2					
WO 2003099829	A1 20031204	WO 2003-US15032	20030513				
W: AE, AG,	AL, AM, AT, AU, AZ	BA, BB, BG, BR, BY,	BZ, CA, CH, CN,				
CO, CR,	CU, CZ, DE, DK, DM	DZ, EC, EE, ES, FI,	GB, GD, GE, GH,				
GM, HR,	HU, ID, IL, IN, IS	JP, KE, KG, KP, KR,	KZ, LC, LK, LR,				
LS, LT,	LU, LV, MA, MD, MG	MK, MN, MW, MX, MZ,	NI, NO, NZ, OM,				
PH, PL,	PT, RO, RU, SD, SE	SG, SK, SL, TJ, TM,	TN, TR, TT, TZ,				
UA, UG,	UZ, VN, YU, ZA, ZM	ZW					
RW: GH, GM,	KE, LS, MW, MZ, SD	SL, SZ, TZ, UG, ZM,	ZW, AM, AZ, BY,				
KG, KZ,	MD, RU, TJ, TM, AT	BE, BG, CH, CY, CZ,	DE, DK, EE, ES,				
FI, FR,	GB, GR, HU, IE, IT	LU, MC, NL, PT, RO,	SE, SI, SK, TR,				
BF, BJ,	CF, CG, CI, CM, GA	GN, GQ, GW, ML, MR,	NE, SN, TD, TG				
AU 2003232125	A1 20031212	AU 2003-232125	20030513				
EP 1507782	A1 20050223	EP 2003-755362	20030513				
R: AT, BE,	CH, DE, DK, ES, FR	GB, GR, IT, LI, LU,	NL, SE, MC, PT,				
IE, SI,	LT, LV, FI, RO, MK	CY, AL, TR, BG, CZ,	EE, HU, SK				
JP 2005526612	T2 20050908	JP 2004-507486	20030513				

PRIORITY APPLN. INFO.:

US 2002-150829 20020520 WO 2003-US15032 20030513

AB A method of preparing a contact mass is provided comprising reacting silicon and a cuprous chloride to form a concentrated, catalytic contact mass.

Furthermore, a method for making an alkylhalosilane using the aforementioned contact mass is provided comprising effecting reaction between an alkyl halide and silicon in the presence of said concentrated contact

mass to produce alkylhalosilane.

В

RX(1) OF 1 2 A ===> **B** 

RX (1)

STAGE(1)

RGT C 7440-21-3 Si, D 7758-89-6 CuCl

CON SUBSTAGE(1) room temperature -> 310 deg C SUBSTAGE(2) 15 minutes, 285 - 310 deg C

STAGE (2)

RCT A 74-87-3

CAT 7440-66-6 Zn, 7440-31-5 Sn

CON 5.8 hours, 330 deg C

PRO B 75-78-5

NTE thermal, optimization study

L74 ANSWER 7 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

139:350849 CASREACT

TITLE: INVENTOR(S): Preparation of organic halosilanes from silicon Ishizaka, Hajime; Ueno, Susumu; Shinohara, Norio; Tanito, Yoichi; Inukai, Tetsuya; Aramata, Mikio

PATENT ASSIGNEE(S):

Shin-Etsu Chemical Industry Co., Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 7 pp.

SOURCE:

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE

JP 2003313191 A2 20031106 JP 2002-117552 20020419
PRIORITY APPLN. INFO.: JP 2002-117552 20020419

OTHER SOURCE(S): MARPAT 139:350849

AB RnHmSiX4-n-m (R = C1-6 hydrocarbyl; X = halo; n, m = 0-3; n + m = 1-3) are prepared by introducing organohalide-containing gases into reactors containing Si.

Cu catalysts, and cocatalysts containing finely dispersed Cs compds. A mixture

of Si powder 90, CsCl-treated Si powder 10, and Cu oxide catalyst 5 weight parts was treated with MeCl at  $320^{\circ}$  under 1.2 kg/cm2 for 6 h to give Me2SiCl2 with 89.1% selectivity.

RX(1) OF 1 2 A ===> **B** 

H<sub>3</sub>C<del>⋅</del>Cl

$$_{2 A} \longrightarrow \frac{(1)}{}$$

В

RX(1) RCT A 74-87-3

RGT C 7440-21-3 Si, D 1344-70-3 Copper oxide

PRO B 75-78-5

CAT 7647-17-8 CsCl

CON 6 hours, 320 deg C

NTE alternative prepn. shown

L74 ANSWER 8 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 139:149752 CASREACT

TITLE: Preparation of silicon-hydrogen bonded

alkyldichlorosilanes

INVENTOR(S): Jung, Il Nam; Yoo, Bok Ryul; Han, Joon Soo; Lim, Weon

Cheol; Kim, Mu Yeol

PATENT ASSIGNEE(S): Korea Institute of Science and Technology, S. Korea

SOURCE: Ger. Offen., 14 pp.

CODEN: GWXXBX

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	API	PLICATION NO.	DATE
DE 10302792	A1	20030807	DE	2003-10302792	20030124
DE 10302792	B4	20040506			
KR 2003065718	Α	20030809	KR	2002-5452	20020130
US 2003166958	<b>A</b> 1	20030904	US	2002-335084	20021231
US 6911552	B2	20050628			
JP 2003238575	A2	20030827	JΡ	2003-22087	20030130
PRIORITY APPLN. INFO.:			KR	2002-5452	20020130
OTHER SOURCE(S):	MA	RPAT 139.149752			

OTHER SOURCE(S): MARPAT 139:149752

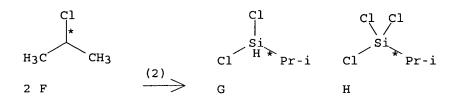
AB A procedure for preparation of silicon-hydrogen bonded alkyldichlorsilanes is described by direct conversion of metallic and/or elemental silicon with a mixture of alkyl chloride and hydrogen chloride or alkyl chloride, which produce hydrogen chloride with reaction temperature, in presence of a copper catalyst. Thus, copper catalyzed reaction of elemental silicon with Me chloride at 340° for 40-70 min gave a mixture of chlorodimethylsilane

and trichloro(methyl)silane.

RX(1) OF 4 3 A ===> B + C

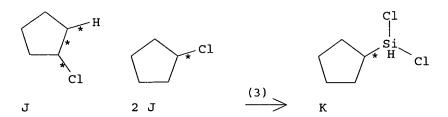
RX(1) RCT A 74-87-3 RGT D 7440-21-3 Si PRO B 1066-35-9, C 75-79-6 CAT 7440-50-8 Cu NTE heating copper and silicon at 350° at first step

RX(2) OF 4 2 F ===> G + H



RX(2) RCT F 75-29-6 RGT D 7440-21-3 Si, I 7647-01-0 HCl PRO G 18191-45-2, H 4170-46-1 CAT 7440-50-8 Cu NTE heating copper and silicon at 220° at first step

RX(3) OF 4 3 J ===> K + L + M



RX(3) RCT J 930-28-9

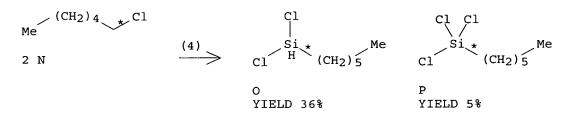
RGT D 7440-21-3 Si

PRO K 143264-36-2, L 14579-03-4, M 142-29-0

CAT 7440-50-8 Cu

NTE HEATING COPPER AND SILICON AT 260.DEGREE. AT FIRST STEP, SICL3 ALSO FORMED

RX(4) OF 4 2 N ===> O + P



RX(4) RCT N 544-10-5

RGT D 7440-21-3 Si, I 7647-01-0 HCl

PRO O 871-64-7, P 928-65-4

CAT 7440-50-8 Cu

NTE heating copper and silicon at 280° at first step

L74 ANSWER 9 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 139:54531 CASREACT

TITLE: Method and effect of catalyst dispersion in direct

synthesis of DDS

AUTHOR(S): Han, Lu; Luo, Wuxi; Liang, Weihua; Wang, Guangrun;

Wang, Jinfu

CORPORATE SOURCE: Department of Chemical Engineering, Tsinghua

University, Beijing, 100084, Peop. Rep. China

SOURCE: Huagong Xuebao (Chinese Edition) (2003), 54(3),

398-402

CODEN: HUKHAI; ISSN: 0438-1157

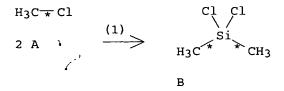
PUBLISHER: Huaxue Gongye Chubanshe, Huagong Xuebao Bianjibu

DOCUMENT TYPE: Journal LANGUAGE: Chinese

AB Based on the synthesis of DDS (dimethyldichlorosilane) in fluidization bed, a new method that can remarkably enhance reactivity and selectivity of the copper-silicon contact mass is investigated exptl. DDS is produced from silicon and Me chloride at about 300° in the direct synthesis process. The catalyst used in this reaction system is active cuprous chloride powder, which usually forms conglomeration of powder. The conglomerate of catalyst is known to be harmful to the synthesis reaction. Treated by ultrasonic energy, conglomeration of active cuprous chloride

catalyst is destroyed, so as to achieve better proportioned dispersion of silicon and catalyst powder. By this means, CuCl catalyst is distributed evenly on the surface of silicon powder, thereby reaction activity and selectivity are increased in the synthesis process of DDS. Using ultrasonic dispersion achieves the same reaction activity with smaller catalyst dosage than the normal dispersion method.

RX(1) OF 1 2 A ===> **B** 



RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si PRO B 75-78-5 CAT 7758-89-6 CuCl CON 290 deg C, 0.3 MPa NTE optimization study, fluidization bed used

L74 ANSWER 10 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 138:24763 CASREACT

TITLE: Direct synthesis of phenylchlorosilanes

AUTHOR(S): Voiculescu, Nicolae

CORPORATE SOURCE: Inst. de Chim. Macromol. "Petru Poni" Iasi, Iasi,

6600, Rom.

SOURCE: Revista de Chimie (Bucharest, Romania) (2002), 53(5),

388-393

CODEN: RCBUAU; ISSN: 0034-7752

PUBLISHER: SYSCOM 18 SRL

DOCUMENT TYPE: Journal LANGUAGE: Romanian

AB The formation of the main products during direct synthesis of phenylchlorosilanes can be reduced to the equation: 2C6H5Cl + Si → Ph2SiCl2. In fact, this reaction is very complicated due to the high temperature and excepting the main products in the reaction mixture, over ten compds. and a residue were identified. A laboratory apparatus was used to establish

the optimum parameters of the direct synthesis, which involved inputting PhCl at 86.60 g/h at  $430^{\circ}$  for 86 h over a 70:30 Si:Cu catalyst, 10 L/h N2; based on Si, the product content included  $26.44^{\circ}$  PhSiCl3 and  $34.03^{\circ}$  Ph2SiCl2. The main reactants of the direct synthesis were monochlorobenzene and Si from domestic sources. Monochlorobenzene was used in mixture with N, the latter being both diluent and fluidizing agent.

RX(1) OF 1 3 A ===> **B** + **C** 

RX(1) RCT A 108-90-7 RGT D 7440-21-3 Si PRO B 98-13-5, C 80-10-4 CAT 7440-50-8 Cu NTE 430°, other products formed

L74 ANSWER 11 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 137:185675 CASREACT

TITLE: Rapid production method for organohalosilanes
INVENTOR(S): Inukai, Tetsuya; Ueno, Susumu; Shinohara, Norio;
Aramata, Mikio; Tanifuji, Yoichi; Ishizaka, Hajime

PATENT ASSIGNEE(S): Shin-Etsu Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 9 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	AP	PLICATION NO.	DATE
JP 2002241384	A2	20020828	JP	2001-37174	20010214
US 2002156310	<b>A1</b>	20021024	US	2002-74025	20020214
US 6506923	B2	20030114			
PRIORITY APPLN. INFO.:	:		JP	2001-37174	20010214
OTHER SOURCE(S):	MA	RPAT 137:185675			

AB Silicon granules react with organohalides RX in the presence of a Cu catalyst and atomized metals to prepare organohalosilanes RnHmSiX4-n-m (R = monovalent hydrocarbyl, X = halo; n, m = 0-3, n + m = 1-3). Thus, MeCl under N reacted in a fluidized-bed reactor containing 100 parts Si, 4 parts powdered Cu, and 0.5 parts atomized Cu at 310° to prepare Me2Cl2Si.

RX(1) OF 1 2 A ===> **B** 

В

RX(1) RCT A 74-87-3 RGT C **7440-21-3** Si PRO B **75-78-5** CAT 7440-50-8 Cu

### NTE 310° under N2, fluidized-bed reactor

L74 ANSWER 12 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

137:20470 CASREACT Method for improving selectivity for TITLE:

dialkyldichlorosilane

INVENTOR(S): Lewis, Larry Neil; Colborn, Robert Edgar; Bablin, John

Matthew

PATENT ASSIGNEE(S): General Electric Company, USA

SOURCE: U.S., 20 pp. CODEN: USXXAM

DOCUMENT TYPE: Patent English LANGUAGE:

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

KIND DATE APPLICATION NO. DATE PATENT NO. ----------\_\_\_\_\_\_ \_ \_ \_ \_ US 6407276 B1 20020618 US 2001-820025 20010329 PRIORITY APPLN. INFO.: US 2001-820025 20010329 A method for forming a dialkyldichlorosilane, comprising reacting elemental silicon with an alkyl chloride using copper as a catalyst together with promoters zinc, tin, and a special promoter. The special promoter is silver, a silver compound, gold, a gold compound, or combinations thereof. The alkyl may be Me such that the dialkyldichlorosilane is dimethyldichlorosilane and the alkyl chloride is Me chloride. The reacting generates the dialkyldichlorosilane in accordance with a first selectivity for the dialkyldichlorosilane that exceeds a second selectivity for the dialkyldichlorosilane. The second selectivity is a selectivity for the dialkyldichlorosilane that would have existed had the special promoter been absent.

THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS REFERENCE COUNT: 18 RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 3 A ===> B + C

H<sub>3</sub>C<del></del>★ Cl 3 A C В

RX (1) RCT A 74-87-3

RGT D 7440-66-6 Zn, E 7440-31-5 Sn, F 7440-21-3 Si, G

7783-90-6 AqCl

PRO B 75-78-5, C 75-79-6

CAT 7440-50-8 Cu SOL 74-87-3 MeCl

NTE fixed bed reactor, alternative prepns. shown

L74 ANSWER 13 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 136:325691 CASREACT

TITLE: Preparation of organohalosilanes

Ishizaka, Hajime; Ueno, Susumu; Shinohara, Norio; INVENTOR(S):

Tanifuji, Yoichi; Inukai, Tetsuya; Aramata, Mikio

PATENT ASSIGNEE(S): Shin-Etsu Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 8 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2002128786	A2	20020509	JP 2000-320538	20001020
US 6395917	B1	20020528	US 2001-981822	20011019
US 2002082437	A1	20020627		

PRIORITY APPLN. INFO.:

JP 2000-320538 20001020

OTHER SOURCE(S): MARPAT 136:325691

AB RnHmSiX(4-n-m) (R = C1-6 hydrocarbyl; X = halo; n, m = 0-3; n + m = 1-3) are prepared by reaction of Si powders with organohalide-containing gases using Cu catalysts and cocatalysts, one or both of which are coated with silica fine powders under shear force. MeCl was treated with Si powder in the presence of electrolytic Cu powder, Zn powder, Sn powder, and fumed silica-coated Cu phosphide powder at 310° under 1.2 kg/cm2 to give silanes at 45.9 g/h with Me2SiCl2 ratio 92.0%.

RX(1) OF 1 2 A ===> **B** 

В

RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si

PRO B **75-78-5** 

CAT 12643-19-5 Copper phosphide, 7631-86-9 SiO2, 7440-50-8 Cu, 7440-66-6 Zn, 7440-31-5 Sn

NTE gas phase

L74 ANSWER 14 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 136:216886 CASREACT

TITLE: Method for promoting dialkyldihalosilane formation

during direct method alkylhalosilane production

INVENTOR(S): Lewis, Larry Neil; Ward, William Jessup; Demoulpied,

David Cheney; Bablin, John Matthew; Gardner, Martha

Maples

PATENT ASSIGNEE(S): General Electric Company, USA

SOURCE: Eur. Pat. Appl., 10 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE

EP 2001-307020 20010817

EP 1184387 A2 20020306

20030115 EP 1184387 Α3

AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,

IE, SI, LT, LV, FI, RO

US 2000-655423 20000905 US 6423860 В1 20020723 JP 2002179685 A2 20020626 JP 2001-266594 20010904

PRIORITY APPLN. INFO.:

US 2000-655423 20000905

A method is described for dialkyldihalosilane (e.g.,

dimethyldichlorosilane) formation during direct method reaction between alkyl halide and powdered silicon in the presence of a catalyst comprising copper, zinc, and aluminum and further comprising an amount of phosphorus and tin.

3 A ===> B + C

H<sub>3</sub>C + Cl 3 A В С

RX (1) RCT A 74-87-3

> RGT D 7440-21-3 Si

PRO B 75-78-5, C 75-54-7

7758-89-6 CuCl, 7440-66-6 Zn, 7440-31-5 Sn

110-54-3 Hexane, 75-09-2 CH2Cl2

product selectivity depends on stoichiometry between catalyst and reagent

RX(2) OF 2 3 A ===> B +

H3C TCl 3 A В J

RX (2) RCT A 74-87-3

> RGT D 7440-21-3 Si

PRO В **75-78-5**, J **75-79-6** 

7758-89-6 CuCl, 7440-66-6 Zn, 7440-31-5 Sn, 1314-84-7 Zinc phosphide (Zn3P2)

SOL 110-54-3 Hexane, 75-09-2 CH2Cl2

NTE product selectivity depends on stoichiometry between catalyst and reagent

L74 ANSWER 15 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

136:53789 CASREACT

TITLE:

The Use of a Fixed-Bed Reactor to Evaluate the

Interactions of Catalysts and Promoters in the Methyl

Chlorosilane Reaction and to Determine the Effect of Cu in the Form of the Eta Phase on This Reaction

AUTHOR(S): Lewis, Larry N.; Ward, William J.

CORPORATE SOURCE: General Electric Research and Development Center,

Niskayuna, NY, 12309, USA

SOURCE: Industrial & Engineering Chemistry Research (2002),

41(3), 397-402

CODEN: IECRED; ISSN: 0888-5885

PUBLISHER: American Chemical Society

DOCUMENT TYPE: Journal LANGUAGE: English

A fixed-bed reactor was employed to study the methylchlorosilane (MCS) reaction, also called the direct process. A copper-silicon contact mass as the main MCS catalyst was used. The copper-silicon contact mass was prepared by the reaction of CuCl with silicon. The effect of added zinc and phosphorus to the MCS reaction was explored, and it was found that, at Cu/Zn ratios > 30, phosphorus addition resulted in an increase in selectivity for dimethyldichlorosilane (Di) at the expense of methyltrichlorosilane (Tri) and residue. Addition of tin to the MCS reaction resulted in an increased overall rate but with a decrease in Di and an increase in disilane formation. Addition of phosphorus and high tin levels resulted in a high rate but with a high selectivity for Di; phosphorus negated the selectivity penalty caused by the addition of tin alone. Phosphorus appeared to cause an increase in formation of the eta phase (Cu3Si), as determined by anal. of MCS beds formed under different conditions. Previously reported arguments show that copper diffusion is operative for Cu-Si renewal in MCS but that Cu diffusion is not the rate-limiting step in the reaction.

REFERENCE COUNT: 33 THERE ARE 33 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 33 A ===> 
$$B + C + D + E + F + G + H + I + J$$

H3C<sup>★</sup>Cl

33 A  $\stackrel{(1)}{\longrightarrow}$ 

RX(1) RCT A 74-87-3
RGT M 7440-21-3 Si
PRO B 75-54-7, C 75-77-4, D 75-79-6, E
75-78-5, F 75-76-3, G 1066-35-9, H 1450-14-2,
I 1560-28-7, J 4342-61-4, K
13528-88-6, L 4518-98-3
CAT 7758-89-6 CuCl, 7440-31-5 Sn
NTE thermal, the Si was doped with trace elements, alternative reaction condITIONS SHOWN, SICL4 AND SIHCL3 ALSO FORMED

L74 ANSWER 16 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 135:344592 CASREACT

TITLE: Preparation and use of a contact mass to effect

production of alkylhalosilanes

INVENTOR(S): Lewis, Larry Neil; Ward, William Jessup, III; Bablin,

John Matthew

PATENT ASSIGNEE(S): General Electric Company, USA

SOURCE: PCT Int. Appl., 18 pp.

CODEN: PIXXD2

DOCUMENT TYPE: Patent

LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

	PAT	CENT I	NO.				DATE		APPLICATION NO.			DATE						
										-								
	WO	2001	0813	54	A:	2	2001	1101		W	20	01-US	55417	7	20010	220		
	WO	2001	0813	54	A.	3	2002	0404										
		W:	ΑE,	AL,	AM,	AT,	AU,	ΑZ,	BA,	BB,	BG,	BR,	BY,	CA,	CH,	CN,	CR,	CU,
			CZ,	DE,	DK,	EE,	ES,	FI,	GB,	GD,	GE,	GH,	GM,	HR,	HU,	ID,	IL,	IN,
			IS,	JP,	KE,	KG,	ΚP,	KR,	ΚZ,	LC,	LK,	LR,	LS,	LT,	LU,	LV,	MD,	MG,
			MK,	MN,	MW,	MX,	NO,	NZ,	PL,	PT,	RO,	RU,	SD,	SE,	SG,	SI,	SK,	SL,
			ТJ,	TM,	TR,	TT,	UA,	UG,	UZ,	VN,	ΥU,	ZW						
		RW:	GH,	GM,	KE,	LS,	MW,	MZ,	SD,	SL,	SZ,	ΤZ,	UG,	ZW,	ΑT,	BE,	CH,	CY,
			DE,	DK,	ES,	FI,	FR,	GB,	GR,	ΙE,	IT,	LU,	MC,	NL,	PT,	SE,	TR,	BF,
			ВJ,	CF,	CG,	CI,	CM,	GA,	GN,	GW,	ML,	MR,	ΝE,	SN,	TD,	TG		
	US	6528	674		В:	l	2003	0304		U	S 20	00-59	53912	2	20000	0420		
	ΕP	1280	733		A:	2	2003	0205		E	P 20	01-9	1285	5	20010	0220		
		R:	AT,	BE,	CH,	DE,	DK,	ES,	FR,	GB,	GR,	IT,	LI,	LU,	NL,	SE,	MC,	PT,
			ΙE,	SI,	LT,	LV,	FI,	RO,	MK,	CY,	ΑL,	TR						
	JΡ	2003	5310	07	T	2	2003	1021		J	P 20	01-5	78442	2	20010	0220		
	RU	2265	073		C	2	2005	1127		RI	J 20	02-13	3115	7	20010	220		
PRIOR	ITI	APP	LN.	INFO	. :					US	S 20	00-5	53912	2	20000	0420		
										W	200	01-US	S541	7	20010	0220		
3.5	_			,			2.1									•		

AB A method for making an alkylhalosilane is provided wherein the method comprises heat treating silicon and a form of copper at a temperature greater

than about 500° to produce a contact mass and effecting reaction between an alkyl halide and silicon in the presence of the contact mass to produce alkylhalosilane. Thus, in a fixed bed reactor, the fixed bed, comprising a silicon contact mass containing 5% copper chloride, 0.05% by reight

zinc dust, and 50 ppm tin dust, was reacted with Me chloride for 1-2 h at 1100° to give chloromethylsilane and dichloromethylsilane.

RX(1) OF 1 2 A ===> **B** + **C** 

RX(1) RCT A 74-87-3 RGT D 7440-66-6 Zn, E 7440-31-5 Sn, F 7440-21-3 Si, G 7758-89-6 CuCl PRO B 75-54-7, C 993-00-0 NTE TEMP.1100 DEGREE

L74 ANSWER 17 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 135:273075 CASREACT

TITLE: Direct process for preparing organochlorosilanes by

use of recovered copper chloride catalyst

INVENTOR(S): Kalchauer, Wilfried; Straussberger, Herbert; Streckel,

Willibald; Goetze, Ulrich

PATENT ASSIGNEE(S): Wacker-Chemie G.m.b.H., Germany

SOURCE: Eur. Pat. Appl., 8 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE ---<del>----</del>---------------EP 1142897 A1 20011010 EP 2001-102109 20010131 R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO US 2001041805 US 2001-814193 **A1** 20011115 20010321 US 6323357 В1 20011127 JP 2001348391 20011218 A2 JP 2001-109034 20010406 PRIORITY APPLN. INFO.: DE 2000-10017153 20000406

AB In CuCl-catalyzed direct synthesis of organochlorosilanes, the copper containing residue was treated with mineral acid which oxidizes the copper to CuCl2 solution Treatment of CuCl2 solution with iron reduces the copper solution

to CuCl solution

REFERENCE COUNT: 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 2 2 A ===> **B** 

$$H_3C \times Cl$$
 $Cl$ 
 $Cl$ 

B YIELD 87%

RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si PRO B 75-78-5

CAT 7758-89-6 CuCl, 1314-13-2 ZnO, 7440-31-5 Sn

RX(2) OF 2 2 A ===> **B** 

H<sub>3</sub>C ★ Cl

 $_{2}$  A  $\stackrel{(2)}{\longrightarrow}$ 

B YIELD 84%

RX(2) RCT A 74-87-3 RGT C **7440-21-3** Si PRO B **75-78-5** 

CAT 1314-13-2 ZnO, 7440-31-5 Sn, 1317-38-0 CuO

L74 ANSWER 18 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 135:227112 CASREACT

TITLE: Procedure for preparation of alkylchlorosilanes by

processing residues from the direct synthesis of

organochlorosilanes

INVENTOR(S): Mautner, Konrad; Tamme, Gudrun; Koehler, Bernd

PATENT ASSIGNEE(S): Wacker-Chemie G.m.b.H., Germany

SOURCE: Ger., 4 pp.
CODEN: GWXXAW

DOCUMENT TYPE: Patent
LANGUAGE: German

LANGUAGE: G FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
DE 10039172 EP 1179534 EP 1179534	C1 A1 B1	20010913 20020213 20020911	DE 2000-10039172 EP 2001-112039	20000810 20010523

R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO US 6344578 20020205 US 2001-915038 В1 20010725 CA 2354299 AA 20020210 CA 2001-2354299 20010730 JP 2002155089 A2 20020528 JP 2001-239495 20010807 JP 3615722 B2 20050202 PRIORITY APPLN. INFO.: DE 2000-10039172 20000810 Alkylchlorosilanes are produced from the liquid components of residues from the direct synthesis of alkylchlorosilanes, which have a b.p. >70° at 1013 hPa and which contain disilanes, by heating the residues with HCl and Si at temps. ≥300°, preferably in a fluidized-bed reactor and preferably ≥400°, whereby simultaneously at least 10 weight % tri- and/or tetrachlorosilane are formed, based on the weight of the alkylchlorosilanes prepared In an example, 70 mL/h high-boiling residues containing 75% disilanes (mixture of 1,1,2,2tetrachlorodimethyldisilane, 1,1,2-trichlorotrimethyldisilane, 1,2-dichlorotetramethyldisilane, and other silanes; b.p >150°) from silane synthesis together with 25 L/h gaseous HCl were fed into an elec. heated laboratory fluidized-bed reactor, 500 mm long and 40 mm inner diameter, filled with 266 g Si, at room temperature, whereupon the reactor was heated to 600° for 20 h, affording 100 g/h of a silane mixture containing approx. 20% HSiCl3 and 40% SiCl4; when the HSiCl3 and SiCl4 were ignored, the silane cleavage products contained 7% MeSiHCl2, 25% MeSiCl3, 12% Me2SiCl2 and 55% other products. In contrast, when a tubular reactor was used, the reaction zone became clogged with solids and silane cracking products after 17 h. REFERENCE COUNT: THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS

RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 2 A + 2 B + 5 C ===> D + E + F + G

С

2 C

$$1/4 \left[ H_3 Si - SiH_3 \right]$$

1/2 (D1-C1)

C1 CH3

$$|*$$
 C1  $|*$ 

D1-Me

C1  $|*$  CH3

 $C1 \times H \times CH_3 \times Si \times CH_3$ 

C1

CH3

C1

CH3

CH3

CH3

RX (1) RCT A 71951-01-4, B 98201-96-8, C 39437-99-5 H 7647-01-0 HCl, I **7440-21-3** Si RGT PRO D 75-54-7, E 75-77-4, F 75-79-6, G 75-78-5 NTE other products formed, fluidized-bed reactor, 600°

L74 ANSWER 19 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

135:166923 CASREACT ACCESSION NUMBER:

TITLE: Preparation of organohalosilanes

Aramata, Mikio; Fujioka, Kazutoshi; Yuyama, Masahiro INVENTOR(S):

PATENT ASSIGNEE(S): Shin-Etsu Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 8 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT:

#### PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2001226382	A2	20010821	JP 2000-34646	20000214
US 2001020108	A1	20010906	US 2001-782190	20010214
US 6339167	B2	20020115		

PRIORITY APPLN. INFO.:

JP 2000-34646 20000214

Title compds. are prepared by reaction of Si with halohydrocarbons in the presence of Cu or Cu compound catalysts and ≥1 accelerator selected from activated Al, Al alloy, and Al4C3 at 250-400° in a steering reactor or fluidized-bed reactor. Powdered silicon was reacted with CH3Cl in the presence of activated alloy (manufactured from aluminum silicide 100, tin 10, and CuCl2 10), zinc oxide, and CuCl2 at 280-300° to give 86.5%

RX(1) OF 1 2 A ===> **B** 

$$H_3C + Cl$$
 $Cl$ 
 $Cl$ 

YIELD 86%

RX(1) RCT A 74-87-3

RGT C 7440-21-3 Si

PRO B 75-78-5

CAT 7447-39-4 CuCl2, 11099-22-2 Aluminum alloy, nonbase, Al, Si, 1314-13-2 ZnO

L74 ANSWER 20 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 134:326620 CASREACT

TITLE: Preparation of organohalosilanes

INVENTOR(S): Aramata, Mikio; Fujimoto, Tatsuya; Saito, Ryuichi; Yuyama, Masahiro; Inukai, Tetsuya; Ishizaka, Hajime

Shin-Etsu Chemical Industry Co., Ltd., Japan PATENT ASSIGNEE(S):

Jpn. Kokai Tokkyo Koho, 8 pp. SOURCE:

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE				
JP 2001122880	A2	20010508	JP 1999-303106	19991025				
US 6288258	B1	20010911	US 2000-694370	20001024				
RITY APPLN. INFO.	:		JP 1999-303106	19991025				
The compds. RnHm	SiX4-n	-m (R = hydroca	rbyl; X = halo; n	, m = 0-4) are				
prepared by reaction of Si with organohalides in the presence of Cu								
catalysts containing 50-10,000 ppm phosphor bronze. Si was reacted with MeCl								
in the presence of a Cu catalyst at 280-300° and linear velocity 7								
cm/s for 72 h to	give	methylchlorosil	ane containing 90	.8 weight% Me2SiCl2.				
	JP 2001122880 US 6288258 RITY APPLN. INFO. The compds. RnHm. prepared by reac catalysts contain	JP 2001122880 A2 US 6288258 B1 RITY APPLN. INFO.: The compds. RnHmSiX4-n prepared by reaction o catalysts containing 5 in the presence of a C	JP 2001122880 A2 20010508 US 6288258 B1 20010911 RITY APPLN. INFO.: The compds. RnHmSiX4-n-m (R = hydroca prepared by reaction of Si with organ catalysts containing 50-10,000 ppm ph in the presence of a Cu catalyst at 2	JP 2001122880 A2 20010508 JP 1999-303106 US 6288258 B1 20010911 US 2000-694370 RITY APPLN. INFO.: JP 1999-303106 The compds. RnHmSiX4-n-m (R = hydrocarbyl; X = halo; n prepared by reaction of Si with organohalides in the p catalysts containing 50-10,000 ppm phosphor bronze. S				

RX(1) OF 1 2 A ===> **B** 

> B YIELD 90%

RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si PRO B 75-78-5

CAT 337378-24-2 Copper alloy, base, Cu 79,P 10,Sn 10, 7440-50-8 Cu, 7440-66-6 Zn

NTE gas phase

L74 ANSWER 21 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 134:207869 CASREACT

TITLE: Synthesis of tris(silyl) methanes by modified direct

process

AUTHOR(S): Lee, Chang Yeob; Han, Joon Soo; Oh, Hyung Sic; Yoo,

Bok Ryul; Jung, Il Nam

CORPORATE SOURCE: Department of Chemistry, Mokpo National University,

Chonnam, 534-729, S. Korea

SOURCE: Bulletin of the Korean Chemical Society (2000),

21(10), 1020-1024

CODEN: BKCSDE; ISSN: 0253-2964

PUBLISHER: Korean Chemical Society

DOCUMENT TYPE: Journal LANGUAGE: English

Direct reaction of elemental Si with a mixture of (dichloromethyl)silanes 1 [Cl3-nMenSiCHCl2: n = 0 (a), n = 1 (b), n = 2 (c), n = 3 (d)] and HCl was studied in the presence of Cu catalyst using a stirred bed reactor equipped with a spiral band agitator at various temps. from 240° to 340°. Tris(silyl)methanes with Si-H bonds, 3a-d [Cl3-nMenSiCH(SiHCl2)2], and 4a-d [Cl3-nMenSiCH(SiHCl2) (SiCl3)], were obtained as the major products and tris(silyl)methanes having no Si-H bonds, 5a-d [Cl3-nMenSiCH(SiCl3)2], as the minor products along with byproducts of bis(chlorosilyl)methanes, derived from the reaction of Si with chloromethylsilane formed by the decomposition of 1. In addition to those products, trichlorosilane and tetrachlorosilane were produced by the reaction of elemental Si with HCl. The decomposition of 1 was suppressed and the production of polymeric carbosilanes reduced by adding HCl to 1. Cd was a good promoter for the reaction, and the optimum temperature for this direct synthesis was 280°.

REFERENCE COUNT: 34 THERE ARE 34 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 4 3 A ===> **B** + **C** + **D** 

D YIELD 18%

RX(1) RCT A 1558-24-3

STAGE(1)

RGT E **7440-21-3** Si CAT 7440-50-8 Cu

STAGE(2)

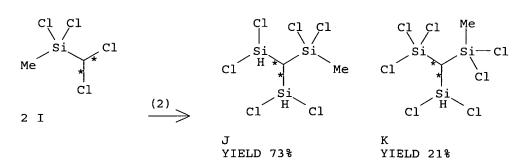
RGT F 7440-43-9 Cd

STAGE(3)

RGT G 7647-01-0 HCl

PRO B 328388-20-1, C 18170-91-7, D 18170-93-9

RX(2) OF 4 2 I ===> **J** + **K** 



RX(2) RCT I 1558-31-2

STAGE(1)

RGT E 7440-21-3 Si

CAT 7440-50-8 Cu

STAGE(2)

RGT F 7440-43-9 Cd

STAGE(3)

RGT G 7647-01-0 HCl

PRO J 166970-83-8, K 166970-84-9

RX(3) OF 4 3 L ===> M + N + O

O YIELD 21%

RX(3) RCT L 18171-59-0

STAGE(1)

RGT E **7440-21-3** Si CAT 7440-50-8 Cu

STAGE(2)

RGT F 7440-43-9 Cd

STAGE(3)

RGT G 7647-01-0 HCl

PRO M 328388-22-3, N 166970-80-5, O 166970-81-6

RX(4) OF 4 3 P ===> Q + R + S

S YIELD 11%

RX(4) RCT P 5926-38-5

STAGE(1)

RGT E **7440-21-3** Si CAT 7440-50-8 Cu

STAGE(2)

RGT F 7440-43-9 Cd

STAGE(3)

RGT G 7647-01-0 HCl

PRO Q 166970-85-0, R 166970-86-1, S 72169-26-7

L74 ANSWER 22 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 133:362839 CASREACT

TITLE: Method for preparation of alkylhalosilanes via

reaction of alkyl halide with powdered silicon in

presence of catalyst and co-catalyst

INVENTOR(S): Hanaoka, Hiroaki; Koyama, Hiroaki; Otani, Eiichi;

Lewis, Larry Neil; Demoulpied, David Cheney; Bablin,

John Matthew

PATENT ASSIGNEE(S): General Electric Company, USA

SOURCE: Eur. Pat. Appl., 6 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
EP 1055675	A2	20001129	EP 2000-304173	20000517

EP 1055675 20010328 Α3 B1 20030521 EP 1055675

R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,

IE, SI, LT, LV, FI, RO

20010116 JP 2000-153897 20000525 JP 2001011082 A2 20001213 CN 2000-108734 20000526 CN 1276375 Α US 1999-136265P 19990527 PRIORITY APPLN. INFO.: US 1999-345540 19990630

A method for making alkylhalosilanes, e.g. methylchlorosilanes, comprising AB reaction of an alkyl halide, e.g. Me chloride, and powdered silicon in the presence of an effective amount of a catalyst and an effective amount of a copper-aluminum co-catalyst with or without the addition of phosphorus. The catalyst typically comprises copper, zinc and tin.

RX(1) OF 1 3 A ===> **B** + **C** 

 $H_3C \times C1$ 3 A В C

RCT A 74-87-3 RX(1)

RGT D 7440-21-3 Si

PRO B 75-78-5, C 75-54-7

CAT 7440-50-8 Cu, 7429-90-5 Al, 7723-14-0 P

NTE flow system; optimized for catalyst components; most aspects claimed

L74 ANSWER 23 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

132:23084 CASREACT

TITLE:

Preparation of alkylhalosilanes by reaction of alkyl halides with carbon monoxide-activated contact mass

containing silicon and copper catalyst

INVENTOR(S):

Armbrust, Ralph; Steiner, Matthias; Schild, Christoph GE Bayer Silicones G.m.b.H. und Co. K.-G., Germany

PATENT ASSIGNEE(S): SOURCE:

PCT Int. Appl., 15 pp.

CODEN: PIXXD2

Patent

DOCUMENT TYPE:

LANGUAGE:

German

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

KIND DATE APPLICATION NO. DATE PATENT NO. \_\_\_\_\_\_ \_\_\_\_\_ \_ \_ \_ \_ -----WO 1999-EP3924 19990608 WO 9964429 Α1 19991216

W: JP, US RW: AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE

DE 1998-19825767 19980609 20000105 DE 19825767 A1 DE 1998-19825767 19980609 PRIORITY APPLN. INFO.:

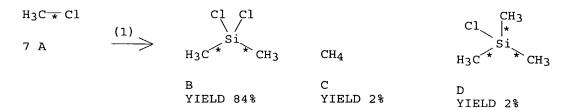
Alkylhalosilanes are prepared by reaction of an alkyl halide, preferably MeCl, with a contact mass consisting of silicon, a catalyst and optionally addnl. promoters, preferably 10-10,000 parts Zn and 5-500 parts Sn per 1 x 106 parts Si at 270-370°, such that the contact mass was activated

by CO at 100-1100°. In an example, CO is conducted through a stirred-bed reactor containing 40 g Si (>99% pure), 3.2 g copper oxide catalyst, and 0.05 g ZnO at 4 L/h at 330° for 3 h, whereupon MeCl is introduced from below into the contact mass at 2 bar absolute pressure at 1.8 L/h to give 84.9% Me2SiCl2, 7% Me3SiCl, and smaller amts. of other products at 7 g/h with an induction time of 27 min, in contrast to an induction time of 72 min in a comparative example where the contact mass is not previously activated by CO. 1

REFERENCE COUNT:

THERE ARE 1 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 7 A ===> B + C + D + E



YIELD 7%

RX (1) RCT A 74-87-3

RGT F 7440-21-3 Si

PRO B 75-78-5, C 74-82-8, D 75-77-4, E

75-79-6

CAT 1314-13-2 ZnO, 7440-50-8 Cu, 1317-39-1 Cu2O, 1317-38-0 CuO

L74 ANSWER 24 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 131:351456 CASREACT

TITLE: Preparation of alkyl (halo) silanes from alkyl halides

and elemental silicon containing phosphorus and tin in

presence of copper catalyst

INVENTOR(S): Margaria, Thomas; Steiner, Mathias Sven; Armbrust,

Ralph

PATENT ASSIGNEE(S): GE Bayer Silicones GmbH & Co. KG, Germany; Pechiney

Electrometallurgie

SOURCE: PCT Int. Appl., 18 pp.

CODEN: PIXXD2

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE --------------------WO 9960001 Α1 19991125 WO 1999-EP3146 19990507 W: JP, US

RW: AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE

DE 19821628 A1 19991125 DE 1998-19821628 19980514 EP 1086110 A1 20010328 EP 1999-923555 19990507 EP 1086110 B1 20030806

1086110 B1 20030806 R: DE, ES, FR, GB, IT

JP 2002515504 T2 20020528 JP 2000-549619 19990507 ES 2207944 T3 20040601 ES 1999-923555 19990507

PRIORITY APPLN. INFO.:

DE 1998-19821628 19980514

WO 1999-EP3146 19990507

AB Alkyl(halo)silanes are prepared by reaction of alkyl halides, preferably MeCl, with Si in presence of a Cu catalyst and, if needed, other promoters, such as 10-10,000 ppm Zn (with respect to Si), at 250-370° such that the Si used contains 250-850 ppm P and 25-85 ppm Sn, preferably with a P:Sn ratio of 4:1-14:1. In examples given, the selectivity for desired product Me2SiCl2 reached 92.9% at 300° and 1000 ppm ZnO when Si containing 640 ppm P and 74 ppm Sn (P:Sn = 8.6:1) was used.

REFERENCE COUNT: 1 THERE ARE 1 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 7 A ===> B + C + D + E

E YIELD 3%

RX(1) RCT A 74-87-3 RGT F 7440-21-3 Si PRO B 75-78-5, C 75-54-7, D 75-77-4, E 75-79-6 CAT 7440-50-8 Cu, 1314-13-2 ZnO, 7440-31-5 Sn, 7723-14-0 P

L74 ANSWER 25 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 129:122762 CASREACT

TITLE: Preparation of alkylhalosilanes from silicon metalloid

powder and alkyl halides

INVENTOR(S): Nakanishi, Tetsuo; Inukai, Tetsuya; Tsukioka, Kazumasa; Nakayama, Hiroshi; Sato, Yukinori

PATENT ASSIGNEE(S): Shin-Etsu Chemical Industry Co., Ltd., Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 5 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE	
JP 10175982	A2	19980630	JP 1996-353019	19961213	
JP 3362619	B2	20030107			
US 5847181	Α	19981208	US 1997-812942	19970304	
RITY APPLN, INFO.	. :		JP 1996-353019	19961213	

OTHER SOURCE(S): MARPAT 129:122762

AB RnSiX4-n (R = C1-4 alkyl; X = halo; n = 0-4) are prepared by feeding alkyl halide-containing gases into reactors containing Si powder and Cu catalysts in the

presence of 3000-10,000 ppm (as P, to the solids) P compds. MeCl was fed into a reactor containing 100 parts Si powder, 4 parts Cu powder, and 4000 ppm/mass Cu phosphide at 330° and 1.3 cm/s for 6 h to result in total methylchlorosilane formation rate 126 g/kg-Si/h, Me2SiCl2 content (to total methylchlorosilanes) 90.8 weight%, and MeSiCl3/Me2SiCl2 ratio 0.048.

RX(1) OF 1 3 A ===> B + C

RX(1) RCT A 74-87-3 RGT D 7440-21-3 Si PRO B 75-79-6, C 75-78-5 CAT 7440-50-8 Cu, 12643-19-5 Copper phosphide NTE 330° 6 h

L74 ANSWER 26 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 127:137351 CASREACT

TITLE: Improved preparation of dialkyldihalosilanes by direct

process in fluidized bed reactor by recycling contact mass dust and controlling reactant gas feed rate

INVENTOR(S): Tsumura, Hiroshi; Nakanishi, Tetsuo; Nakayama,

Hiroshi; Satoh, Yukinori

PATENT ASSIGNEE(S): Shin-Etsu Chemical Co., Ltd., Japan

SOURCE: Eur. Pat. Appl., 11 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE

----EP 784057 A1 EP 784057 B1 A1 19970716 EP 1997-300137 19970110 20020904 R: DE, FR, GB JP 09194490 A2 US 5712405 A 19970729 JP 1996-22111 19960112 US 1997-781207 19980127 19970110 PRIORITY APPLN. INFO.: JP 1996-22111 19960112 OTHER SOURCE(S): MARPAT 127:137351

RnSiX4-n (R = lower alkyl group with 1-4 carbons; X = halogen; n = 0-4) were prepared by using a fluidized bed reactor equipped with a feed line for reactant gas and a delivery line for product gas, charging the reactor with a contact mass comprising metallic Si powder and a Cu catalyst, and feeding a reactant gas containing an alkyl halide through the feed line into the reactor whereby the silane is formed by direct synthesis. A dust collector is connected to the delivery line for collecting the contact mass carried over with the product gas, which is fed back to the reactor. The feed of the reactant gas is controlled such that a linear velocity multiplied by a d. may range from 0.2-2 kg/m2·sec. A product mixture of 92.2% Me2SiCl2 and 3.8% MeSiCl3 was obtained while maintaining a reaction rate of 720 kg/h when a fluidized bed with diameter of 80 mm and height of 1140 mm, a temperature of 290°, a contact mass of 100 parts of metallic Si powder with mean particle size of 60  $\mu m$  and 2.7 parts of a catalyst mixture of metallic Cu, Zn and Sb powders, a reactant gas feed superficial linear velocity of 0.135 m/s and d. of 2.14 kg/m3, and a cyclone + filter for collecting dust were used; lower reaction rates and percentages of dichlorodimethylsilane were obtained using other conditions.

### RX(1) OF 1 2 A ===> **B** + **C**

 $H_3C \times C1$  C1 C1

RX(1) RCT A 74-87-3

RGT D 7440-21-3 Si

PRO B 75-78-5, C 75-79-6

CAT 7440-50-8 Cu, 7440-66-6 Zn, 7440-36-0 Sb

SOL 7727-37-9 N2

NTE contact mass dust recycled; reactant gas feed rate controlled; fluidized bed reactor

L74 ANSWER 27 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 126:186201 CASREACT

TITLE: Preparation of alkyl halo silanes

INVENTOR(S): Steiner, Matthias; Schild, Christoph; Degen, Bruno

PATENT ASSIGNEE(S): Bayer A.-G., Germany

SOURCE: Ger., 4 pp.

CODEN: GWXXAW

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 1

#### PATENT INFORMATION:

PATENT NO.	KINI	DATE	API	PLICATION NO.	DATE
DE 1953231	C1	19970206	DE	1995-19532315	19950901
EP 760371	A2	19970305	EP	1996-113288	19960820
EP 760371	A3	19980325			
EP 760371	B1	20021127			
R: DE	ES, FR, C	B, NL			
US 5679823	A	19971021	US	1996-703242	19960826
AU 9664301	A1	19970306	AU	1996-64301	19960827
AU 703621	B2	19990325			
JP 09194488	3 A2	19970729	JP	1996-242508	19960827
CN 1149056	Α	19970507	CN	1996-111459	19960830
CN 1066737	В	20010606			

PRIORITY APPLN. INFO.:

DE 1995-19532315 19950901

AB Alkyl chloro silanes, of which Me2SiCl2 is the major component, are prepared by reaction of Si with alkyl halides (preferably MeCl) in presence of at least one catalyst (Rochow reaction) such that the reaction is performed in the presence of volatile or gaseous halo- and/or alkoxy-substituted sulfur compds., preferably SOCl2, SO2Cl2, SCl2, and/or S2Cl2, and, if necessary, other promoters such as Sn, Zn, P, and Al, alone or in combination and in elemental form or as a compound In an example, 40 g silicon (particle size 71-160μm), 3.2 g Cu catalyst, and 0.05 g ZnO were homogenized and then treated with MeCl at 2 bar at 1.8 L/h at 300° to give 6.1 g/h product, of which 1.9% is MeHSiCl2 byproduct, 1.9% are high-boiling byproducts, and the MeSiCl3/Me2SiCl2 (T/D) selectivity ratio is 0.070; addition of 10μL SOCl2 at the beginning of the reaction afforded an improved T/D of 0.066 and suppressed the byproducts to 1.5% MeHSiCl2 and 1.3% high-boiling compds.

# RX(1) OF 1 A ===> **B**

RX(1) RCT A 74-87-3 RGT C **7440-21-3** Si PRO B **75-78-5** CAT 7440-50-8 Cu, 1314-13-2

CAT 7440-50-8 Cu, 1314-13-2 ZnO, 7719-09-7 SOC12 NTE Other products formed

L74 ANSWER 28 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 126:60007 CASREACT

TITLE: Direct Synthesis of Tris(chlorosilyl)methanes

Containing Si-H Bonds

AUTHOR(S): Han, Joon Soo; Yeon, Seung Ho; Yoo, Bok Ryul; Jung, Il

Nam

CORPORATE SOURCE: Organometallic Chemistry Laboratory, Korea Institute

of Science and Technology, Seoul, 130-650, S. Korea

SOURCE: Organometallics (1997), 16(1), 93-96

CODEN: ORGND7; ISSN: 0276-7333

PUBLISHER: American Chemical Society

DOCUMENT TYPE: Journal LANGUAGE: English

Direct reaction of elemental Si with a mixture of CHCl3 and HCl was studied in the presence of a Cu catalyst using a stirred reactor equipped with a spiral band agitator at various temps. from 280 to 340°.

Tris(chlorosilyl)methanes (CH(SiH2Cl)(SiHCl2)2, CH(SiHCl2)3, CH(SiCl3)(SiHCl2)2, CH(SiCl3)2(SiHCl2), and CH(SiCl3)3) with Si-H bonds were obtained as the major products along with byproducts of bis(chlorosilyl)methanes, derived from the reaction of Si with CH2Cl2 formed by the decomposition of CHCl3, and trichlorosilane and tetrachlorosilane produced from the reaction of elemental Si with HCl. The decomposition of CHCl3 was suppressed and the production of polymeric carbosilanes reduced by adding HCl to CHCl3. The deactivation problem of elemental Si due to the decomposition of CHCl3 and polycarbosilanes was eliminated. Cd was a good promoter for the reaction, while Zn is an inhibitor for this particular reaction.

REFERENCE COUNT: 32 THERE ARE 32 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

RX(1) OF 1 4 A ===> B + C + D +

B C YIELD 6% YIELD 45%

D E YIELD 16% YIELD 3%

RX(1) RCT A 67-66-3

RGT F 7440-21-3 Si, G 7647-01-0 HCl

PRO B 185308-41-2, C 158362-26-6, D 18170-91-7, E 18170-93-9

CAT 7440-43-9 Cd, 7440-50-8 Cu

NTE FLOW SYSTEM, Temp. AFFECTS YIELDS AND DISTRIBUTION, ADDING ZINC TO THE COPPER CATALYST INHIBITS THE REACTION, RATIO OF REACTANTS ALSO AFFECTS YIELD AND DISTRIBUTION OF PRODUCTS, OTHER PRODUCTS ALSO FORMED

L74 ANSWER 29 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 125:114743 CASREACT

TITLE: Effects of hydrogen chloride addition to the direct

reaction of methylene chloride with elemental silicon

AUTHOR(S): Yeon, Seung Ho; Han, Joon Soo; Yoo, Bok Ryul; Jung, Il

Nam

CORPORATE SOURCE: Organometallic Chemistry Lab., Korea Institute of

Science and Technology, PO Box 131, Cheongryang,

Seoul, 130-650, S. Korea

SOURCE: Journal of Organometallic Chemistry (1996), 516(1-2),

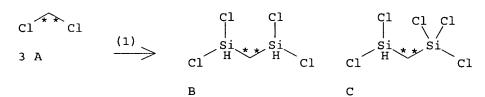
91-95

CODEN: JORCAI; ISSN: 0022-328X

PUBLISHER: Elsevier DOCUMENT TYPE: Journal LANGUAGE: English

AB Direct synthesis of bis(chlorosily1) methanes was restudied by reacting elemental Si simultaneously with CH2Cl2 and HCl in the presence of Cu catalyst using a stirred reactor equipped with a spiral band agitator at a carefully controlled temperature between 260 and 340°.

Bis (dichlorosily1) methane and (dichlorosily1) (trichlorosily1) methane were obtained as the major products and bis (trichlorosily1) methane as a minor product along with trichlorosilane and tetrachlorosilane derived from the reaction between elemental Si and HCl. The decomposition of CH2Cl2 was suppressed and the production of polymeric carbosilanes reduced by adding HCl to the CH2Cl2 reactant. The optimum mixing ratio of CH2Cl2 and HCl for the direct synthesis of bis(sily1) methanes was 1:4. The deactivation problem of elemental Si owing to decompns. of CH2Cl2 and polycarbosilanes was eliminated. Cd was a good promoter for the reaction, while Zn is an inhibitor for this particular reaction.



D

RX(1) RCT A 75-09-2

RGT E 7440-21-3 Si, F 7440-43-9 Cd, G 7647-01-0 HCl

PRO B 18081-42-0, C 18171-02-3, D

4142-85-2

CAT 7440-50-8 Cu

NTE METHYL CHLORIDE ALSO DETECTED

L74 ANSWER 30 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 124:56297 CASREACT

TITLE: Preparation of trissilylmethane derivatives INVENTOR(S): Tei, Kazuo; Nobu, Norihiro; Kan, Junshu

PATENT ASSIGNEE(S): Korea Institute of Science and Technology, Japan

SOURCE: Jpn. Kokai Tokkyo Koho, 10 pp.

CODEN: JKXXAF

DOCUMENT TYPE: Patent LANGUAGE: Japanese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 07196670	A2	19950801	JP 1993-310854	19931210
JP 2951524	B2	19990920		

PRIORITY APPLN. INFO.: JP 1993-310854 19931210

OTHER SOURCE(S): MARPAT 124:56297

Claimed are R1R2R3SiCHR4R5 [R1 = R2 = R3 = methyl; or R1 = Me, R2 = R3 = Cl; or R1 = Cl, R2 = R3 = methyl; R4 = R5 = SiHCl2; or R4 = SiHCl2, R5 = SiCl3 ]. Treatment of (dichloromethyl)dimethylchlorosilane with HCl and Si in the presence of Si/Cu catalyst and Cd at 280° gave 55.1% 1,1,3-trichloro-3-methyl-2-(dichlorosilyl)-1,3-disilabutane, 18.5% 1,1,3-trichloro-3-methyl-2-(trichlorosilyl)-1,3-disilabutane, and other minor byproducts.

## RX(1) OF 3 2 A ===> B + C

RX(1) RCT A 18171-59-0 RGT D 7647-01-0 HCl, E **7440-21-3** Si PRO B **166970-80-5**, C **166970-81-6** CAT 7440-50-8 Cu, 7440-43-9 Cd NTE 280°

RX(2) OF 3 2 H ===> I + J

RX(2) RCT H 1558-31-2

RGT D 7647-01-0 HCl, E **7440-21-3** Si PRO I **166970-83-8**, J **166970-84-9** CAT 7440-50-8 Cu, 7440-43-9 Cd NTE 280°

RX(3) OF 3 2 K ===> **L** + **M** 

RX(3) RCT K 1558-24-3 RGT D 7647-01-0 HCl, E 7440-21-3 Si PRO L 18170-91-7, M 18171-02-3 CAT 7440-50-8 Cu, 7440-43-9 Cd NTE 280°

L74 ANSWER 31 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 123:257007 CASREACT

TITLE: Monosilane preparation by aluminum trichloride

catalyzed hydrogenation of high-boiling residue from organohalide reaction with silicon metalloid (direct

process)

INVENTOR(S): Ferguson, Stephen P.; Jarvis, Robert F., Jr.; Naasz,

Brian M.; Oltmanns, Kimberly K.; Warrick, Gordon L.;

Whiteley, Darrel L.

PATENT ASSIGNEE(S): Dow Corning Corp., USA

SOURCE: U.S., 5 pp.
CODEN: USXXAM

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

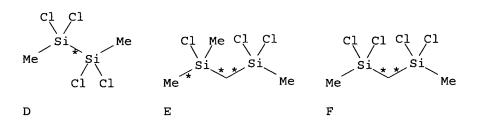
PATENT INFORMATION:

PATENT NO.	KIND	DATE	API	LICATION NO.	DATE
US 5430168	Α	19950704	US	1994-329758	19941027
EP 709389	A1	19960501	ΕP	1995-307516	19951023
EP 709389	B1	20000209			
R: DE, FR, G	B, IT				
JP 08208666	A2	19960813	JΡ	1995-280860	19951027
JP 3650185	B2	20050518			
ORITY APPLN. INFO.:			US	1994-329758	19941027

PRIORITY APPLN. INFO.: OTHER SOURCE(S): MARPAT 123:257007

Monosilanes, RyHzSiX4-y-z (R = C1-C6 alkyl, aryls, C1-C6 alkoxy, Me3Si, trifluoropropyl; X = halogen; y = 0-3; z = 0-3; yr+z = 0-3) were prepared from the high-boiling residue resulting from the reaction of organohalides with Si metalloid (direct process) by mixing an organotrihalosilane, RSiX3, and the high-boiling residue in the presence of H2 gas and a catalytic amount of AlCl3. The present process results in consumption of the organotrihalosilane rather than a net increase which typically occurs in processes for hydrogenation of the high-boiling residue. At least a portion of the catalytic amount of AlCl3 may be formed in situ during the direct process and isolation of the high-boiling residue. Thus, the high boiling residue from the reaction of MeCl with Si was reacted with H2 and MeSiCl3 in the presence of 0.55 weight % AlCl3 at 1252 psig and 325° for 2.8 h resulting in 91% conversion to RyHzSiX4-y-z; the result was 37% without the AlCl3.

RX(1) OF 5 ...3 A + 8 B ===>  $\mathbf{C}$  +  $\mathbf{D}$  +  $\mathbf{E}$ 



RX(1) RCT A 74-87-3, B 75-54-7 RGT G 7440-21-3 Si PRO C 13528-88-6, D 4518-98-3, E 4519-04-4, F 4519-03-3 NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(2) OF 5 2 A ===> **B** + **H...** 

RX(2) RCT A 74-87-3

STAGE(1)

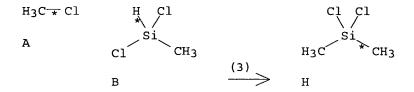
RGT G 7440-21-3 Si

STAGE(2)

RGT I 1333-74-0 H2 CAT 7446-70-0 AlCl3

PRO B 75-54-7, H 75-78-5 NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(3) OF 5 ...A + B ===> **H** 



RX(3) RCT A 74-87-3, B 75-54-7

STAGE(1)

RGT G 7440-21-3 Si

STAGE(2)

RGT I 1333-74-0 H2 CAT 7429-90-5 Al

PRO H 75-78-5

NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(4) OF 5 COMPOSED OF RX(2), RX(1)RX(4) 12 A ===> C + D + E + F

RX(2) RCT A 74-87-3

STAGE(1)

RGT G 7440-21-3 Si

STAGE(2)

RGT I 1333-74-0 H2 CAT 7446-70-0 AlCl3

PRO B 75-54-7, H 75-78-5 NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(1) RCT A 74-87-3, B 75-54-7 RGT G **7440-21-3** Si PRO C **13528-88-6**, D 4518-98-3, E 4519-04-4, F 4519-03-3

NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(5) OF 5 COMPOSED OF RX(2), RX(3)RX(5) 3 A ===>  $\mathbf{H}$ 

$$H_3C \star C1$$
  $H_3C \star C1$  2  $C1 C1$  2  $C1 \times C1$  2  $H_3C \star CH_3$ 

RX(2) RCT A 74-87-3

STAGE(1)

RGT G 7440-21-3 Si

STAGE (2)

RGT I 1333-74-0 H2 CAT 7446-70-0 AlCl3 PRO B 75-54-7, H **75-78-5** 

NTE OTHER MINOR PRODUCTS ALSO ISOLATED

RX(3) RCT A 74-87-3, B 75-54-7

STAGE(1)

RGT G 7440-21-3 Si

STAGE(2)

RGT I 1333-74-0 H2 CAT 7429-90-5 Al

PRO H 75-78-5

NTE OTHER MINOR PRODUCTS ALSO ISOLATED

L74 ANSWER 32 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 121:301071 CASREACT

TITLE: Alkenylchlorosilanes and direct synthesis thereof INVENTOR(S): Jung, Il N.; Yeon, Seung H.; Lee, Bong W.; Yoo, Bok R. PATENT ASSIGNEE(S): Korea Institute of Science and Technology (KIST), S.

Korea

SOURCE: U.S., 8 pp.

CODEN: USXXAM

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
US 5338876	Α	19940816	US 1993-75134	19930610
KR 9502860	B1	19950327	KR 1992-10292	19920613
JP 07101962	A2	19950418	JP 1993-142014	19930614
JP 08032711	B4	19960329		
PRIORITY APPLN. INFO.	:		KR 1992-10292	19920613

OTHER SOURCE(S): MARPAT 121:301071

AB Alkenylchlorosilanes R1CH:CHCH2SiCl2R2 (R1 represents H, Me, SiHCl2 SiCl3 or CH2SiCl3 and R2 represents H or Cl) were prepared by reacting Si metal with a mixed gas comprising of R3CH:CHCHClR4 (R3 represents H or Cl and R4 represents H, Me or CH2Cl) and HCl or R5Cl (R5 represents H, Cl-C4 alkyl or CH2CH2Cl) in the presence of a Cu catalyst at 220-350°.

## RX(1) OF 2 A ===> B

B YIELD 71%

RX(1) RCT A 107-05-1

RGT C 7440-21-3 Si, D 7647-01-0 HCl

PRO B 3937-28-8

CAT 7440-50-8 Cu NTE REACTOR AT 300 .DEGREES., OTHER PRODUCTS FORMED

RX(2) OF 2 2 F ===> G + H

RX(2) RCT F 563-52-0

RGT C 7440-21-3 Si, D 7647-01-0 HCl

PRO G 69238-76-2, H 69238-77-3

CAT 7440-50-8 Cu

NTE REACTOR AT 300.DEGREES., OTHER PRODUCTS FORMED

L74 ANSWER 33 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 121:57569 CASREACT

TITLE: Interaction of copper catalysts and Si(100) for the

direct synthesis of methylchlorosilanes

AUTHOR(S): Floquet, Nicole; Yilmaz, Sefa; Falconer, John L. CORPORATE SOURCE: Dep. Chem. Eng., Univ. Colorado, Boulder, CO,

80309-0424, USA

SOURCE: Journal of Catalysis (1994), 148(1), 348-68

CODEN: JCTLA5; ISSN: 0021-9517

DOCUMENT TYPE: Journal LANGUAGE: English

ΔR Single crystal Si(100) surfaces with a native oxide layer were reacted with Me chloride to investigate the direct synthesis of dimethyldichlorosilane. These high purity silicon surfaces are excellent models of the reacting powders used industrially for direct synthesis. The oxide layer did not appear to inhibit reaction significantly. The copper catalyst was added to the surface by various methods, and the form of the catalyst necessary for selective reaction was determined Reaction was carried out at atmospheric pressure in a recirculating batch reactor and the copper-silicon surfaces were characterized before and after reaction by XRD, SEM, EDS, AES, and optical microscopy. Catalysts that contained only metallic Cu or only Cu2O did not catalyze dimethyldichlorosilane formation; both Cu and Cu20 were needed. A mixture containing 82 wt% Cu and 18 wt% Cu20 yielded the best selectivity [65 mol% (CH3)2SiCl2, 33 mol% CH3SiCl3, and 2 mol% (CH3)3SiCl]. This selectivity is comparable to those obtained in fluidized bed reactors for copper-silicon powders without promoters. Both CuCl and Cu(HCOO) 2·2H2O catalysts were also selective for dimethyldichlorosilane formation initially, but methyldichlorosilane formed at longer reaction times. Copper formate dihydrate solution decomposed to form Cu/Cu20 mixts. on Si(100). Because the Cu percentage was lower than 82%, however, and because formate decomposition also formed a Cu film on the surface, the selectivity was lower. Most of the catalysts reacted with silicon to form the stoichiometric alloy Cu3Si, but some of the resulting surfaces did not react to form methylchlorosilanes. The competition between Cu3Si formation and consumption to form methylchlorosilanes was different for the different catalysts. A correlation was seen between epitaxial growth of Cu3Si on

Si(100) and poor selectivity for dimethyldichlorosilane formation. The most selective surfaces had a randomly oriented Cu3Si phase. The Si(100) surface reacted by forming square pyramidal pits with Si(111) sides; the pits contained Cu3Si.

RX(1) OF 1 2 A ===> B + C + D

RX(1) RCT A 74-87-3 RGT E 7440-21-3 Si PRO B 75-78-5, C 75-79-6, D 75-77-4 CAT 7440-50-8 Cu, 1317-39-1 Cu20 NTE Thermal; 598 K; Surface reaction

L74 ANSWER 34 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 120:323654 CASREACT

TITLE: Formation of organosilicon compounds. 112. The

influence of reaction conditions on the reaction of

(Cl3Si)2CCl2 with silicon. The structures of

2,2,3,3,5,5,6,6-octachloro-1,4-bis(trichlorosily1)-

2,3,5,6-tetrasilabicyclo[2.1.1]hexane and

1,1,3,4,6,6-hexakis(trichlorosilyl)hexatetraene Fritz, G.; Beetz, A. G.; Matern, E.; Peters, K.;

Peters, E. M.; von Schnering, H. G.

CORPORATE SOURCE: Inst. Anorg. Chem., Univ. Karlsruhe, Karlsruhe,

Germany

SOURCE: Zeitschrift fuer Anorganische und Allgemeine Chemie

(1994), 620(1), 136-44

CODEN: ZAACAB; ISSN: 0044-2313

DOCUMENT TYPE: Journal LANGUAGE: German

GI

AUTHOR(S):

 $\begin{array}{c|c} \text{Cl}_2\text{Si} & \text{SiCl}_2 \\ \hline \text{Cl}_2 & \text{Si} \\ \text{Cl}_3\text{Si} & \text{SiCl}_3 \\ \hline \text{Si} & \text{Cl}_2 & \text{I} \end{array}$ 

AB While reactions of (Cl3Si)2CCl2 1 with Si(Cu) in a fluidized bed at 320° exclusively yield products by silylation of the CCl2 group in 1, the reaction in a stirred bed preferably gives rise to chlorosilanes containing C-C double and triple bonds. The reaction of 1 with elemental copper by dehalogenation at carbon gives Cl3SiC.tplbond.CSiCl3 3,

(Cl3Si)2C:C:C(SiCl3)2 4, and (Cl3Si)2C:C(SiCl3)2 11. In the reaction of 1 with CaSi2 no addnl. Si-C bonds are formed, exclusively chlorosilanes with multiple C-C bonds as 3, 4 and (Cl3Si)2C:C:C(SiCl3)C(SiCl3):C:C(SiCl3)2 10 were found besides of SiCl4. The structures of the bicyclo[2.1.1]hexane 6 (shown as I) and the hexatetraene 10 were determined by x-ray crystallog. The skeleton of 6 is a system of high bond stress with 2-C2 symmetry. The strongly folded (138.8°) four-membered ring (sum of angles =  $344.2^{\circ}$ ) and the presence of both a Si-Si bond length of 238.2 pm and a Si-Si non-bonding distance of 255.1 pm are remarkable aspects of this feature. The mean bond lengths in the bicyclic compound were found to be .hivin.d(Si-C) = 190.9 pm and .hivin.d(Si-C) = 185.1 pm for exo- and endocyclic bonds, resp. The skeleton of 10 has 2/m-C2h symmetry. In the planar six-membered chain the central C-C single bond length and the mean distance of the cumulated double bonds are 148.6 pm and 130.5 pm, resp.

$$RX(3) OF 3$$
 7 A ===> **H** + **B** + **C** + **I** + **J** + **K**

J YIELD 1%

```
STRUCTURE
DIAGRAM
IS NOT
AVAILABLE
```

K YIELD 2%

RX(3) RCT A 18157-09-0 RGT L 7440-21-3 Si PRO H 4775-58-0, B 18038-55-6, C 18083-41-5, I 153110-29-3, J 153110-30-6, K 154960-13-1 CAT 7440-50-8 Cu NTE thermal

L74 ANSWER 35 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 120:134609 CASREACT

TITLE: Formation of organosilicon compounds. 110. Reactions

of dichlorobis(trichlorosily1) methane and its silicon

methylated derivatives as well as of

chlorobis (trichlorosily1) methane 1-chloro-1,1-

bis(trichlorosilyl)ethane and 2,2-dichloropropane with

silicon (copper catalyst)

AUTHOR(S): Fritz, G.; Lauble, S.; Befurt, R.; Peters, K.; Peters,

E. M.; von Schnering, H. G.

CORPORATE SOURCE: Inst. Anorg. Chem., Univ. Karlsruhe, Karlsruhe,

Germany

SOURCE: Zeitschrift fuer Anorganische und Allgemeine Chemie

(1993), 619(9), 1494-511

CODEN: ZAACAB; ISSN: 0044-2313

DOCUMENT TYPE: Journal LANGUAGE: German

The reactions of (Cl3Si)2CCl2 1, its Si-methylated derivs. (Me3Si)2CCl2 8, Me3SiCCl2SiMe2Cl 9, (ClMe2Si)2CCl2 10, Me3SiCCl2SiMeCl2 11, Cl2MeSiCCl2SiCl3 12 as well as of (Cl3Si)2CHCl 38, (Cl3Si)2CClMe 39 and of Me2CCl2 with Si (Cu cat.) in a fluid bed reactor (38 and 39 also in a stirred solid bed reactor) are presented. While 1 yields C(SiCl3)4 2, the 1,1,3,3-tetrachloro-2,2,4,4-tetrakis(trichlorosilyl)-1,3-disilacyclobutane Si6C2Cl16 3 and the related C-spiro linked disilacyclobutanes Si8C3Cl20 4, Si10C4Cl24 5, Si12C5Cl28 6 and Si14C6Cl32 7, these types of compds. are not obtained starting from the Si-methylated derivs. 8, 9, 10 or 11. They produce a number of variously Si-chlorinated and -methylated tetrasila- and trisilamethanes. However, 12 forms Si-chlorinated trisilamethanes and the disilacyclobutanes Si6C2Cl15Me 34, cis- and trans-Si6C2Cl14Me2 35, as well as the spiro-linked disilacyclobutanes 4, Si8C3Cl19Me 36 and Si8C3Cl18Me2 (Cl3Si)2CHCl 38 mainly yields HC(SiCl3)3 31 and also the disilacyclobutanes cis- and trans-(Cl3Si)HC(SiCl2)2C(SiCl3)H 41 and (Cl3Si)2C(SiCl2)2C(SiCl3)H 45, the 1,3,5-trisilacyclohexane [(Cl3Si)HCSiCl2]3 44 as well as (Cl3Si)2CH-CH(SiCl3)2 and [(Cl3Si)2CH]2SiCl2. (Cl3Si)2CClMe 39 mainly yields (Cl3Si)2C:CH2 and (Cl3Si)2CHMe besides HC(SiCl3)3, MeC(SiCl3)3 and Cl2MeSiC(SiCl3)3. Me2CCl2 59 mainly yields Me(Cl)C:CH2, Me2CHCl and HCl2SiCMe2SiCl3 besides Me2C(SiCl3)2 and Me2C(SiCl2H)2. Crystal structures of compds. 3 and 4 were determined The disilacyclobutane ring of compound 3 is planar, showing a mean distance of d(Si-C) = 191.8 pm and the usual deformations of endocyclic angles:  $\alpha Si = 94.2^{\circ} > 85.8^{\circ} = \alpha C$ . The spiro-linked disilacyclobutane rings of compound 4 are slightly folded by a mean angle of 19.0°.

RX(1) OF 3 23 A ===> B + C + D + R + F + G

Cl Cl Cl Cl Cl Cl Cl Cl Cl 
$$\alpha$$
 Cl Cl Cl  $\alpha$  Cl Cl  $\alpha$  Cl Cl  $\alpha$  Cl Cl Cl  $\alpha$  Cl Cl Cl Cl Cl  $\alpha$  Cl Cl Cl Cl  $\alpha$  Cl Cl Cl Cl Cl Cl Cl  $\alpha$  Cl Cl Cl Cl Cl Cl  $\alpha$  Cl Cl Cl  $\alpha$  Cl Cl Cl  $\alpha$  Cl  $\alpha$ 

D

E

STRUCTURE
DIAGRAM
IS NOT
AVAILABLE

F

G

RX(2) OF 3 4 J ===> K + L + M + N + O

Searched by John DiNatale

RX(2) RCT J 15951-41-4
RGT H 7440-21-3 Si, I 7440-50-8 Cu
PRO K 5926-35-2, L 153110-33-9, M
153110-34-0, N 153110-57-7, O 153110-58-8
NTE thermal, 300°

RX(3) OF 3 12 P ===> Q + R + S + T + T + T + T + T

\* STRUCTURE DIAGRAM TOO LARGE FOR DISPLAY - AVAILABLE VIA OFFLINE PRINT \*

Т

\* STRUCTURE DIAGRAM TOO LARGE FOR DISPLAY - AVAILABLE VIA OFFLINE PRINT \*

RX(3) RCT P 70058-64-9

RGT H 7440-21-3 Si, I 7440-50-8 Cu PRO Q 153110-43-1, R 153110-44-2, S 18077-04-8, T 153110-47-5, U 153110-49-7, V 153110-50-0

NTE thermal, 300°, other products were also obsd.

L74 ANSWER 36 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 120:30807 CASREACT

TITLE: Problems and solutions involved in direct synthesis of

allylchlorosilanes

AUTHOR(S): Yeon, Seung Ho; Lee, Bong Woo; Kim, Sun Il; Jung, Il

Nam

CORPORATE SOURCE: Organomet. Chem. Lab., Korea Inst. Sci. Technol.,

Seoul, 130-650, S. Korea

SOURCE: Organometallics (1993), 12(12), 4887-91

CODEN: ORGND7; ISSN: 0276-7333

DOCUMENT TYPE: Journal LANGUAGE: English

AB Direct synthesis of allylchlorosilanes was reinvestigated by reacting elemental silicon simultaneously with allyl chloride and hydrogen chloride in the presence of copper catalyst using a stirred reactor equipped with a spiral band agitator at a carefully controlled temperature between 220 and 320°. Allyldichlorosilane was obtained as the major product and allyltrichlorosilane as a minor product along with trichlorosilane and tetrachlorosilane derived from the reaction between elemental silicon and hydrogen chloride, but diallyldichlorosilane was obtained only in a trace amount The decomposition of allyl chloride was suppressed and the production

of

diallyldichlorosilane reduced by adding hydrogen chloride to the allyl chloride reactant. The polymerization problem in the distillation process of

the

products due to diallyldichlorosilane was eliminated. Cadmium was a good promoter for the reaction, while zinc was found to be an inhibitor.

$$RX(1)$$
 OF 3 4 A ===> **B** + **C** + **D**

D YIELD 38%(64)

$$RX(2)$$
 OF 3 2 A ===> **B** + **C**

$$RX(3)$$
 OF 3 2 A ===> **B** + **C**

$$_{\text{H}_2\text{C}}$$

2 A  $\xrightarrow{\text{(3)}}$ 

RX(3) RCT A 107-05-1 RGT E 7440-21-3 Si, G 7647-01-0 HCl PRO B 3937-28-8, C 107-37-9 CAT 7440-50-8 Cu, 7440-43-9 Cd

NTE stirred reactor equipped with spiral band agitator, other products formed

L74 ANSWER 37 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 119:226044 CASREACT

TITLE: Direct synthesis of 2,2-dichloro-2-silaindan AUTHOR(S): Jung, Il Nam; Yeon, Seung Ho; Han, Joon Soo

CORPORATE SOURCE: Organometallic Chem. Lab., Korea Inst. Sci. Technol.,

Seoul, 130-650, S. Korea

SOURCE: Bulletin of the Korean Chemical Society (1993), 14(3),

315-16

CODEN: BKCSDE; ISSN: 0253-2964

DOCUMENT TYPE: Journal LANGUAGE: English

GI

AB A convenient direct synthesis of 2,2-dichloro-2-silaindan (I) comprises reacting metallic Si with 1,2-(ClCH2)2C6H4 in the presence of Cu catalyst in a stirred reactor equipped with a spiral band agitator at 260-320°. At 280°, compound I was prepared in 51% yield along with 2% dechlorinated derivative II, 3% o-xylene, 3% tetrahydrodibenzocyclooctene III, and 41% decomposition products.

RX(1) OF 1 A ===> B

Cl
$$Cl$$

$$Si$$

$$Si$$

$$Cl$$

$$A$$

$$YIELD 51%$$

RX(1) RCT A 612-12-4 RGT C 7440-21-3 Si PRO B 20151-87-5 CAT 7440-50-8 Cu SOL 108-88-3 PhMe NTE 280° in reactor, other products formed

L74 ANSWER 38 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 119:203627 CASREACT

TITLE: Method for making organohalosilanes

INVENTOR(S): Webb, Steven W.; Ritzer, Alan; Neely, John D.

PATENT ASSIGNEE(S): General Electric Co., USA

SOURCE: U.S., 3 pp.

CODEN: USXXAM

DOCUMENT TYPE: Patent LANGUAGE: English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
US 5243061	Α	19930907	US 1992-987872	19921209
EP 602850	A1	19940622	EP 1993-309666	19931202
R: DE, FR,	GB			
JP 06239874	A2	19940830	JP 1993-307606	19931208
JP 3563425	B2	20040908		
PRIORITY APPLN. INFO	. :		US 1992-987872	19921209

AB Organohalosilanes were prepared by reaction between an organic halide and a mixture of silicon powder and spent contact mass generated during the production

of organohalosilanes. Thus, treating the above mixture with MeCl in the presence of copper/brass catalyst gave MeSiCl3 and Me2SiCl2.

$$RX(1)$$
 OF 1 2 A ===> **B** + **C**

RX(1) RCT A 74-87-3

RGT D 7440-21-3 Si

PRO B 75-79-6, C 75-78-5

NTE spent contact mass as addn. reactant

L74 ANSWER 39 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 119:72666 CASREACT

TITLE: Direct synthesis of bis(sily1) methanes containing

silicon-hydrogen bonds

AUTHOR(S): Jung, Il Nam; Yeon, Seung Ho; Han, Joon Soo

CORPORATE SOURCE: Organomet. Chem. Lab., Korea Inst. Sci. Technol.,

Seoul, 130-650, S. Korea

SOURCE: Organometallics (1993), 12(6), 2360-2

CODEN: ORGND7; ISSN: 0276-7333

DOCUMENT TYPE: Journal LANGUAGE: English

As series of Si-H-containing bis(silyl) methanes has been prepared by reacting directly elemental silicon simultaneously with (chloromethyl) silanes and hydrogen chloride in the presence of a copper catalyst using a stirred reactor equipped with a spiral band agitator at carefully controlled temps. between 280 and 340°. Bis(silyl) methanes containing dichlorosilyl groups, e.g., Me3SiCH2SiCl2H, were obtained as the major products and trichlorosilyl-group-containing bis(silyl) methanes as minor products. Cadmium was a good promoter for the reaction, whereas zinc was found to be an inhibitor.

#### RX(1) OF 1 2 A ===> B + C

Cl Me

Cl Me

Cl Me

Cl Me

Si Si

Me

2 A

$$(1)$$

B

YIELD 58%

Cl Me

Cl Me

Si

Si

Cl

Cl

Cl

Cl

Cl

C YIELD 14%

RX(1) RCT A 1719-57-9

RGT D 7647-01-0 HCl, E 7440-21-3 Si

PRO B 54296-27-4, C 16538-60-6

CAT 7440-50-8 Cu

L74 ANSWER 40 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 116:174424 CASREACT

TITLE: Direct synthesis of methylchlorosilaalkanes

INVENTOR(S): Jung, Il Nam; Lee, Gyu Hwan; Yeon, Seung Ho; Suk, Mi

Yeon

PATENT ASSIGNEE(S): Korea Institute of Science and Technology, S. Korea

SOURCE: U.S., 7 pp.
CODEN: USXXAM

DOCUMENT TYPE: Patent

LANGUAGE:

English

FAMILY ACC. NUM. COUNT: 3

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
US 5075477	Α	19911224	US 1991-697165	19910508
DE 4111822	Cl	19920402	DE 1991-4111822	19910411
JP 06340676	A2	19941213	JP 1991-262501	19910917
JP 08019140	B4	19960228		
PRIORITY APPLN. INFO.	:		KR 1991-1055	19910122

OTHER SOURCE(S):

MARPAT 116:174424

AB A novel and improved method for simultaneously producing 2,4,6-trisilaheptane, MeSiR2CH2SiCl2CH2SiR2Me, and 1,3-disilabutane, MeSiR2CH2SiCl3 (R = Cl, Me), the starting materials for the preparation of silicon polymers, is claimed. The method consists of reacting Si with chloromethylsilanes, MeSiR2CH2Cl, at 250-350° in the presence of Cu as catalyst exclusively or together with Cd powder as cocatalyst. Thus, 100 g of Si/Cu contact mixture obtained from Si and CuCl was charged in an agitating-type reaction bath. After increasing the temperature in the reactor to 320°, 189 g Me2SiClCH2Cl was added through a dropping funnel while N2 was also blown at the rate of 60 mL/min. Workup of the reaction mixture after completion gave 54.2% Me2SiClCH2SiCl2CH2SiMe2Cl along with 12.7% Cl3SiCH2SiMe2Cl and 33.1% byproduct.

$$RX(1)$$
 OF 2 3 A ===> **B** + **C**

$$RX(2)$$
 OF 2 3 A ===> **B** + **C**

YIELD 2%

YIELD 13%

RX(2) RCT A 1719-57-9 RGT D **7440-21-3** Si PRO B **38050-12-3**, C **16538-60-6** CAT 7758-89-6 CuCl NTE thermal, 320°

L74 ANSWER 41 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 116:152011 CASREACT

TITLE: Process and catalyst containing a lanthanide compound

as promoter for the direct synthesis of

dimethyldichlorosilane

INVENTOR(S): Plagne, Jean Louis; Godde, Guy; Cattoz, Roland

PATENT ASSIGNEE(S): Rhone-Poulenc Chimie SA, Fr. SOURCE: Eur. Pat. Appl., 13 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: French

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO. DATE
EP 470020	A1	19920205	EP 1991-420283 19910730
EP 470020	B1	19950104	
R: DE, DK,	ES, FR	, GB, GR	
FR 2665446	A1	19920207	FR 1990-10011 19900731
FR 2665446	B1	19921127	
AU 9179317	A1	19920206	AU 1991-79317 19910625
BR 9103211	A	19920526	BR 1991-3211 19910726
JP 04288088	A2	19921013	JP 1991-211452 19910730
JP 07002753	B4	19950118	
US 5117030	Α	19920526	US 1991-738540 19910731
PRIORITY APPLN. INFO	.:		FR 1990-10011 19900731
	_		6 44 43 3 41

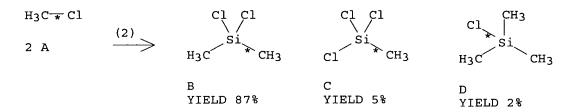
AB Me2SiCl2 was prepared by reaction of MeCl and Si over a catalyst consisting of Cu or a Cu compound and promoted by 10-1000 ppm Sn or Sb (or Sn or Sb compds.), 0-3% metallic Zn or Zn compound), 0-3% metallic Zn or Zn compound, 0.01-2% lanthanide compound, and 0.05-2% alkali metal or alkali metal compound Thus, 210 g Si was reacted with MeCl (16 L/h) at 345° for 1 h, then at 315° for the duration of the reaction, in the presence of a catalyst consisting of 16.3 g CuCl, 0.38 g of a bronze containing 10% (by weight)

Sn, 1.60 g ZnCl2, and 1.69 g K3LaCl6. The yields were: 93.6% Me2SiCl2, 2.8% MeSiCl3, and 1.7% Me3SiCl, with 58% conversion of Si.

# RX(1) OF 3 2 A ===> B + C + D

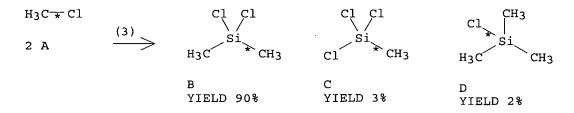
RX(1) RCT A 74-87-3 RGT E 7440-21-3 Si PRO B 75-78-5, C 75-79-6, D 75-77-4 CAT 7758-89-6 CuCl, 7440-31-5 Sn, 7646-85-7 ZnCl2, 13600-81-2 Lanthanate(3-), hexachloro-, tripotassium, (OC-6-11)-

RX(2) OF 3 2 A ===> **B** + **C** + **D** 



RX(2) RCT A 74-87-3 RGT E 7440-21-3 Si PRO B 75-78-5, C 75-79-6, D 75-77-4 CAT 7758-89-6 CuCl, 7440-31-5 Sn, 7646-85-7 ZnCl2, 10099-58-8 LaCl3

RX(3) OF 3 2 A ===> **B** + **C** + **D** 



RX(3) RCT A 74-87-3 RGT E 7440-21-3 Si PRO B 75-78-5, C 75-79-6, D 75-77-4 CAT 7758-89-6 CuCl, 7440-31-5 Sn, 7646-85-7 ZnCl2, 7447-40-7 KCl

L74 ANSWER 42 OF 46 CASREACT COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 115:183439 CASREACT

TITLE: Direct synthesis of trisilaalkanes

AUTHOR(S): Jung, Il Nam; Lee, Gyu Hwan; Yeon, Seung Ho; Suk, Mi

Yeon

CORPORATE SOURCE: Organomet. Chem. Lab., Korea Inst. Sci. Technol.,

Seoul, 130-650, S. Korea

SOURCE: Bulletin of the Korean Chemical Society (1991), 12(4),

445-9

CODEN: BKCSDE; ISSN: 0253-2964

DOCUMENT TYPE: Journal LANGUAGE: English

AB A series of trisilaalkanes, e.g., Me2SiClCH2SiCl2CH2SiMe2Cl, has been

prepared in high yields by the direct reaction of  $\alpha\mbox{-}$ 

chloromethylsilanes with elemental silicon in the presence of copper catalyst using a reactor equipped with a spiral band agitator at the carefully controlled temperature between 280 and 340°. Disilaalkane compds. were obtained as minor products. Cadmium was a good promotor for the reactions, while zinc was an inhibitor.

RX(1) OF 3 2 A ===> **B** 

B YIELD 82%

RX(2) OF 3 2 F ===> **G** + **H** 

G YIELD 87%

Н

YIELD 6%

RX (2) RCT F 1558-25-4 C 7440-21-3 Si RGT

> PRO G 18420-19-4, H 16538-62-8

7758-89-6 CuCl CAT

NTE 280-340°

RX(3) OF 3 3 F ===> I + J

F 1558-25-4 RX(3) RCT RGT C **7440-21-3** Si I 16538-67-3, J 4142-85-2 PRO CAT 7758-89-6 CuCl NTE 280-340°

L74 ANSWER 43 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

115:114601 CASREACT

TITLE: Silicon-containing heterocyclic compounds. LVII.

Direct synthesis of 9,9,10,10-tetrachloro-9,10-disila-

9,10-dihydroanthracene and its derivatives

AUTHOR (S):

Chernyshev, E. A.; Komalenkova, N. G.; Shashkov, I. A. Gos. Nauchno-Issled. Inst. Khim. Tekhnol. Elementoorg.

Soedin., USSR

CORPORATE SOURCE:

Zhurnal Obshchei Khimii (1991), 61(3), 758-62

CODEN: ZOKHA4; ISSN: 0044-460X

DOCUMENT TYPE:

Journal

LANGUAGE:

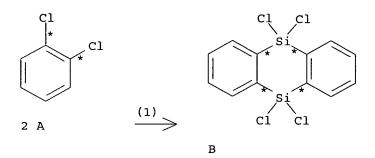
SOURCE:

Russian

GI

AB Two methods are reported for increasing the degree of depletion of solid reagent (Si/Cu) and improving the yield of the title compound (I) in its direct synthesis involving reaction of o-dichlorobenzene (II) with Si/Cu at 520-540°: (i) periodic treatment of the solid reagent surface with HCl in the absence of II (increasing depletion of Si/Cu from 20-25% to 60-70%), and (ii) simultaneous introduction of II and 10% hexachlorodisilane (40-50% increase in the rate of production of I).

# RX(1) OF 1 2 A ===> **B**



RX(1) RCT A 95-50-1

RGT C 7440-21-3 Si, D 13465-77-5 Si2Cl6

PRO B **32962-41-7**CAT 7440-50-8 Cu

L74 ANSWER 44 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 114:164496 CASREACT

TITLE: Preparation of alkylhalosilanes via copper catalyzed

and metal promoted reaction of silicon with alkyl

halide

INVENTOR(S):
Degen, Bruno; Felder, Kurt; Licht, Elke; Wagner,

Gebhard

PATENT ASSIGNEE(S): Bayer A.-G., Germany

SOURCE: Eur. Pat. Appl., 6 pp.

CODEN: EPXXDW

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO. DATE
EP 416406	A2	19910313	EP 1990-116308 19900825
EP 416406	A3	19920527	
EP 416406	В1	19961120	
R: DE, E	S, FR, GB,	IT	
DE 3929865	A1	19910314	DE 1989-3929865 19890908
US 5068385	Α	19911126	US 1990-570089 19900820
ES 2094739	Т3	19970201	ES 1990-116308 19900825
JP 03109391	A2	19910509	JP 1990-232611 19900904
JP 2925273	B2	19990728	
CA 2024803	AA	19910309	CA 1990-2024803 19900906

BR 9004428	Α	19910910	BR 1990-4428	19900906
ZA 9007131	Α	19910731	ZA 1990-7131	19900907
DD 298930	A5	19920319	DD 1990-343894	19900907
MIDDA VTTONIO	INFO ·	•	DE 1989-3929865	19890908

AB Process for the preparation of alkylhalosilanes by the reaction of Si with alkyl halides in the presence of copper as catalyst and promoters is claimed. The promoters are P as well as P compds. in combination with In as well as indium compds. and/or Al as well as Al compds. Thus, reaction of Si (40g) with MeCl (2 bar) at 300° in the presence of Cu (3.2g), ZnO (0.05g), In (0.004g), and P (0.056g) gave 1.7% of Me3SiCl, 0.017% mixture of MeSiCl3/Me2SiCl2, and 3.7% of polysilanes and others at the production rate of 6.0 g/h.

$$RX(1) OF 1 2 A ===> B + C + D$$

RX(1) RCT A 74-87-3
RGT E 7723-14-0 P, F 7440-74-6 In, G 1314-13-2 ZnO, H
7440-21-3 Si
PRO B 75-77-4, C 75-79-6, D 75-78-5
CAT 7440-50-8 Cu
NTE 300°, Thermal

L74 ANSWER 45 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 111:39442 CASREACT

TITLE: Direct formation of chlorodimethylsilane from silicon

and chloroform

AUTHOR(S): Magrini, Kimberly A.; Falconer, John L.; Koel, Bruce

Ε.

CORPORATE SOURCE: Dep. Chem. Eng., Univ. Colorado, Boulder, CO,

80309-0424, USA

SOURCE: Journal of Physical Chemistry (1989), 93(14), 5563-8

CODEN: JPCHAX; ISSN: 0022-3654

DOCUMENT TYPE: Journal LANGUAGE: English

AB A Cu-catalyzed reaction procedure was found for the selective formation of Me2HSiCl from the direct reaction of MeCl with solid Si. The new procedure is a two-step process. A Cu/Si sample is prepared by evaporating Cu onto clean polycryst. Si under ultrahigh vacuum, and the Cu/Si surface is first activated by exposure to 10% HSiCl3/MeCl at 598 K. After the HSiCl3/MeCl mixture is evacuated from the reactor, the activated Cu/Si surface is reacted in fresh MeCl. For low surface concns. of Cu, the partially hydrogenated silane, Me2HSiCl, is selectively produced. Cl3SiH was also found to activate polycryst. Si (in the absence of Cu) for production of highly chlorinated methylchlorosilanes at a much higher rate than on the Cu/Si surface, but with poor selectivity to Me2HSiCl. All reactions are carried out at atmospheric pressure in a reactor that is attached to an ultrahigh-vacuum chamber. This allows surface anal. by Auger electron spectroscopy, which detected SiClx on reacted surfaces. These SiClx sites, which appear necessary for methylchlorosilane formation, are

apparently formed during activation by HSiCl3.

RX(1) OF 1 A ===> **B** 

> B YIELD 90%

RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si PRO B 1066-35-9 CAT 7440-50-8 Cu

L74 ANSWER 46 OF 46 CASREACT COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 106:214018 CASREACT

TITLE: Catalysis of the Rochow direct process

AUTHOR(S): Ward, W. J.; Ritzer, A.; Carroll, K. M.; Flock, J. W.

CORPORATE SOURCE: Corp. Res. Dev. Cent., General Electric Co.,

Schenectady, NY, 12301, USA

SOURCE: Journal of Catalysis (1986), 100(1), 240-9

CODEN: JCTLA5; ISSN: 0021-9517

DOCUMENT TYPE: Journal LANGUAGE: English

AB Variables affecting Me2SiCl2 (I) synthesis from Si and MeCl were examined Fluidized and stirred bed reactors were used. Trace quantities of Sn affect the process profoundly, and the effects of Sn and Zn were synergistic. A catalyst system consisting of Cu, Zn, and Sn was discovered which yielded 90% I with nearly complete Si utilization. This is a major improvement over the best previously reported performance.

RX(1) OF 1 A ===> **B** 

H<sub>3</sub>C<del>⋅</del>Cl

 $A \qquad \xrightarrow{(1)}$ 

Cl Cl Si H3C \* CH3

B YIELD 90%

RX(1) RCT A 74-87-3 RGT C 7440-21-3 Si PRO B 75-78-5 CAT 7440-50-8 Cu, 7440-66-6 Zn, 7440-31-5 Sn

L75 ANSWER 1 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN

```
2004:413565 CAPLUS
ACCESSION NUMBER:
DOCUMENT NUMBER:
                         142:83329
                         Refractive index at infrared wavelengths and
TITLE:
                         dielectric permittivity of pure and fluorinated
                         silicon dioxide from measurements of their thin films
                         deposited on Si
                         Power, G.; Vij, J. K.; Shaw, M.
AUTHOR (S):
                         Department of Electronic and Electrical Engineering,
CORPORATE SOURCE:
                         Trinity College, University of Dublin, Dublin, 2, Ire.
                         Journal of Physics D: Applied Physics (2004), 37(9),
SOURCE:
                         1362-1370
                         CODEN: JPAPBE; ISSN: 0022-3727
                         Institute of Physics Publishing
PUBLISHER:
DOCUMENT TYPE:
                         Journal
LANGUAGE:
                         English
     The Fourier-transform IR (FTIR) spectra of silicon dioxide (SiO2) and
     fluorinated silicon dioxide (SiOF) deposited on bare Si wafers have been
     recorded and the interference fringes in the spectra have been used to
     estimate the refractive index, n, of the SiO2 and SiOF films. It is found
     from the FTIR spectra that n is reduced by 3.5% on doping with F atoms.
     The refractive indexes and thicknesses of the films were also determined by
     ellipsometry for comparison. The complex capacitance, C^*(\omega) = C'-
     iC'', of samples from the wafers has been measured in the frequency range
     1 Hz-1.8 GHz with broadband dielec. spectroscopy. Two relaxation peaks,
     one centered at .apprx.1 kHz and the other in the 10-100 MHz range are
     observed in both the SiO2 and SiOF coated wafer samples. The measurements of
     C*(w) are related to the frequency-dependent complex permittivity,
     \varepsilon^*(\omega) = \varepsilon' - i\varepsilon'' of the films with the use
     of simple equivalent circuit models. & Shows a reduction of 16% on
     fluorine addition It is suggested that the origin of the high frequency peak
     is the RC network formed by the wafer substrate and the dielec. film,
     while the low frequency peak results from charged defects at the Si-SiO2
                 The dielec. results are compared with the microwave
     dielec. measurements, made using a different method, on both bare Si
     wafers and wafers coated with dielec. films, which have been reported
     recently. The observed dispersion in C' and peaks in C'' are a result of the
     layered metal-oxide-silicon structure of the samples.
     76-9 (Electric Phenomena)
     Section cross-reference(s): 73
     7782-44-7, Oxygen, reactions
                                    7783-61-1, Tetrafluorosilane
     7803-62-5, Silane, reactions
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (plasma; refractive index at IR wavelengths and dielec. permittivity of
        pure and fluorinated silicon dioxide from measurements of their thin
        films deposited on Si)
     7631-86-9P, Silica, properties 116305-88-5P, Silicon fluoride
TТ
     RL: PNU (Preparation, unclassified); PRP (Properties); PREP
     (Preparation)
        (refractive index at IR wavelengths and dielec. permittivity of pure
        and fluorinated silicon dioxide from measurements of their thin films
        deposited on Si)
     7803-62-5, Silane, reactions
IT
     RL: RCT (Reactant); RACT (Reactant or reagent)
```

(plasma; refractive index at IR wavelengths and dielec. permittivity of pure and fluorinated silicon dioxide from measurements of their thin films deposited on Si)

RN 7803-62-5 CAPLUS

CN Silane (8CI, 9CI) (CA INDEX NAME)

SiH4

IT 116305-88-5P, Silicon fluoride oxide

RL: PNU (Preparation, unclassified); PRP (Properties); PREP (Preparation)

(refractive index at IR wavelengths and dielec. permittivity of pure and fluorinated silicon dioxide from measurements of their thin films deposited on Si)

RN 116305-88-5 CAPLUS

CN Silicon fluoride oxide (9CI) (CA INDEX NAME)

Component	Ratio	Component
		Registry Number
=======================================	+============	+=============
0	×	17778-80-2
F	x	14762-94-8
Si	x	7440-21-3

REFERENCE COUNT: 25 THERE ARE 25 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L75 ANSWER 2 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2003:837093 CAPLUS

DOCUMENT NUMBER: 139:307891

TITLE: Process for producing halosilanes from silicon and

mixtures of halogens, hydrogen and/or halogen-containing compounds by impinging

microwave energy

INVENTOR(S):
Auner, Norbert

PATENT ASSIGNEE(S): Wacker-Chemie G.m.b.H., Germany; Dow Corning

 ${\tt Corporation}$ 

SOURCE: PCT Int. Appl., 17 pp.

CODEN: PIXXD2

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.			KIN	D :	DATE APPLICATION NO.				DATE								
					_									_			
WO 2003087107			A2		20031023 WO 2003-DE1270				20030415								
WO 2	003	0871	07		A3		2003	1204									
	W:	ΑE,	AG,	AL,	AM,	ΑU,	ΑZ,	BA,	BB,	BR,	BY,	ΒZ,	CA,	CN,	CO,	CR,	CU,
		DM,	DZ,	EC,	GD,	GE,	GH,	GM,	HR,	ID,	IL,	IN,	IS,	JP,	ΚE,	KG,	ΚP,
		KR,	ΚZ,	LC,	LK,	LR,	LS,	LT,	LV,	MA,	MD,	MG,	MK,	MN,	MW,	MX,	MZ,
		NO,	NZ,	OM,	PH,	PL,	RO,	RU,	SD,	SG,	SL,	ТJ,	TM,	TN,	TT,	TZ,	UA,
		ŪĠ,	US,	UZ,	VN,	ΥU,	ZA,	ZM,	zw								
	RW:	GH,	GM,	KE,	LS,	MW,	MZ,	SD,	SL,	SZ,	TZ,	UG,	ZM,	ZW,	AM,	AZ,	BY,
		KG,	KZ,	MD,	RU,	ΤJ,	TM,	AΤ,	BE,	BG,	CH,	CY,	CZ,	DE,	DK,	EE,	ES,
		FI,	FR,	GB,	GR,	HU,	ΙE,	IT,	LU,	MC,	NL,	PT,	RO,	SE,	SI,	SK,	TR,
		BF,	ВJ,	CF,	CG,	CI,	CM,	GA,	GN,	GQ,	GW,	ML,	MR,	NE,	SN,	TD,	TG
DE 10222728		A1		2003	1204	]	DE 2	002-	1022	2728		2	0020	523			

```
Α1
                                 20031106
                                             DE 2002-10227041
                                                                     20020617
    DE 10227041
     AU 2003236776
                          A1
                                 20031027
                                             AU 2003-236776
                                                                     20030415
     EP 1495033
                          A2
                                 20050112
                                             EP 2003-735264
                                                                     20030415
             AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,
             IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK
                          A1
                                 20050630
                                             US 2003-510583
                                                                     20030415
     US 2005143592
                                 20050727
                                             CN 2003-808605
                                                                     20030415
     CN 1646542
                          Α
     JP 2005522508
                          T2
                                 20050728
                                             JP 2003-584063
                                                                     20030415
                                             DE 2002-10217139
                                                                  Α
                                                                     20020417
PRIORITY APPLN. INFO.:
                                             DE 2002-10222728
                                                                  Α
                                                                     20020523
                                             DE 2002-10227041
                                                                  Α
                                                                     20020617
                                             WO 2003-DE1270
                                                                     20030415
                         CASREACT 139:307891; MARPAT 139:307891
OTHER SOURCE(S):
     Halogen-containing silanes RaHbSiXc [R = (un)substituted C1-10 alkyl or aryl
     in which \geq 1 C atoms can be replaced by CO, CO2, O, S, SO, SO2, NH or NR', where R' = (un)substituted C1-20 alkyl; X = F, Cl, Br; a = 0-3, b
     = 0-3, c = 1-4, and a + b + c = 4] are prepared by reaction of Si in
     presence of microwave energy with a gaseous atmospheric of mixts. of
     elements or compds. selected from among halogens, halogens and
     organohalogen compds., halogens and hydrogen, halogens and hydrogen
     halides, organohalogen compds. (alkyl or aryl halides, preferably MeCl),
     organohalogen compds. and hydrogen, organohalogen compds. and hydrogen
     halide, hydrogen halides, fluorosilanes and hydrogen, fluorosilanes and
     hydrogen halides, hydrogen-containing chlorosilanes and hydrogen,
     hydrogen-containing chlorosilanes and hydrogen halides, organohalosilanes and
     hydrogen, organohalosilanes and hydrogen halides or hydrocarbons
     (preferably methane or ethane) and hydrogen halides. Elemental Si used
     may be crystalline or amorphous, or mixts. of both, or in the form of a silicon
     alloy, preferably ferrosilicon, and the process may be carried out in
     presence of a metal or metal-containing catalyst or promotor, preferably Cu.
     This process uses much less energy and is thus more economical for production
     of halosilanes than prior art. In the example given, reaction of 98.5%
     ferrosilicon with a 1:1 gaseous mixture of MeCl and Ar with
     microwave irradiation gave 6.4% MeSiCl3, 82% Me2SiCl2 and 11.6%
     Me3SiCl.
TC
     ICM C07F007-02
CC
     29-6 (Organometallic and Organometalloidal Compounds)
     Section cross-reference(s): 45, 49, 78
     halosilane prepn process microwave irradn
ST
IT
     Silanes
     RL: IMF (Industrial manufacture); RCT (Reactant); SPN (Synthetic
     preparation); PREP (Preparation); RACT (Reactant or reagent)
        (chloro; process for preparation of halosilanes from silicon and mixts. of
        halogens, hydrogen and/or halogen-containing compds. by using
        microwave irradiation)
IT
     Silanes
     RL: IMF (Industrial manufacture); RCT (Reactant); SPN (Synthetic
     preparation); PREP (Preparation); RACT (Reactant or reagent)
        (fluoro; process for preparation of halosilanes from silicon and mixts. of
        halogens, hydrogen and/or halogen-containing compds. by using
        microwave irradiation)
     Silanes
IT
     RL: IMF (Industrial manufacture); SPN (Synthetic preparation); PREP
     (Preparation)
        (halosilanes; process for preparation of halosilanes from silicon and mixts.
        of halogens, hydrogen and/or halogen-containing compds. by using
        microwave irradiation)
```

IT Microwave

(irradiation; process for preparation of halosilanes from silicon and mixts. of

halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Halides

RL: RCT (Reactant); RACT (Reactant or reagent)

(organic; process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Hydrogen halides

RL: RCT (Reactant); RACT (Reactant or reagent)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT 75-79-6P, Trichloro(methyl)silane

RL: BYP (Byproduct); SPN (Synthetic preparation); PREP

(Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using **microwave** irradiation)

IT 7440-50-8, Copper, uses

RL: CAT (Catalyst use); USES (Uses)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using **microwave** irradiation)

IT 75-78-5P, Dichloro(dimethyl) silane

RL: IMF (Industrial manufacture); SPN (Synthetic preparation); PREP (Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using **microwave** irradiation)

IT 74-82-8, Methane, reactions 74-84-0, Ethane, reactions 74-87-3, Methyl
 chloride, reactions 1333-74-0, Hydrogen, reactions 7440-21-3,
 Silicon, reactions 7647-01-0, Hydrogen chloride, reactions 7664-39-3,
 Hydrogen fluoride, reactions 7783-61-1, Silicon tetrafluoride
 8049-17-0, Ferrosilicon

RL: RCT (Reactant); RACT (Reactant or reagent)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using **microwave** irradiation)

IT 75-77-4P, Chloro(trimethyl)silane, preparation

RL: SPN (Synthetic preparation); PREP (Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT 75-79-6P, Trichloro(methyl)silane

RL: BYP (Byproduct); SPN (Synthetic preparation); PREP

(Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using **microwave** irradiation)

RN 75-79-6 CAPLUS

CN Silane, trichloromethyl- (6CI, 8CI, 9CI) (CA INDEX NAME)

IT 75-78-5P, Dichloro(dimethyl)silane

RL: IMF (Industrial manufacture); SPN (Synthetic preparation); PREP

(Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

RN 75-78-5 CAPLUS

CN Silane, dichlorodimethyl- (8CI, 9CI) (CA INDEX NAME)

IT 7440-21-3, Silicon, reactions

RL: RCT (Reactant); RACT (Reactant or reagent)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

RN 7440-21-3 CAPLUS

CN Silicon (7CI, 8CI, 9CI) (CA INDEX NAME)

Si

IT 75-77-4P, Chloro(trimethyl)silane, preparation

RL: SPN (Synthetic preparation); PREP (Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

RN 75-77-4 CAPLUS

CN Silane, chlorotrimethyl- (8CI, 9CI) (CA INDEX NAME)

L75 ANSWER 3 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1999:760007 CAPLUS

DOCUMENT NUMBER: 131:338994

TITLE: Manufacture of trichlorosilane by reduction of

tetrachlorosilane in fluidized bed

INVENTOR(S): Griesshammer, Rudolf; Koppl, Franz; Schreieder, Franz

PATENT ASSIGNEE(S): Wacker-Chemie GmbH, Germany

SOURCE: Faming Zhuanli Shenqing Gongkai Shuomingshu, 4 pp.

CODEN: CNXXEV

DOCUMENT TYPE: Patent LANGUAGE: Chinese

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

```
PATENT NO.
                        KIND
                                          APPLICATION NO.
                                -----
                        ----
                                           ______
                               19970702
    CN 1153138
                         Α
                                           CN 1996-120113
                                                                  19960923
PRIORITY APPLN. INFO.:
                                           CN 1996-120113
    The process comprises constituting a fluidized bed of Si granules,
    microwave-heating Si to 110-300°, reacting the HSiCl3 with
    SiCl4 and H2 in the fluidized bed while adding Si granules continuously,
    collecting the product gas, separating SiHCl3 from the gas product, and feeding
    back remnant gas to reactor. The SiHCl4 in remnant gas may be pyrolyzed
     in sedimentation reactor to obtain Si.
IC
    ICM C01B033-107
    49-8 (Industrial Inorganic Chemicals)
CC
    1333-74-0, Hydrogen, reactions 7440-21-3, Silicon, reactions
     10026-04-7, Tetrachlorosilane
    RL: PEP (Physical, engineering or chemical process); RCT
     (Reactant); TEM (Technical or engineered material use); PROC
     (Process); RACT (Reactant or reagent); USES (Uses)
        (in manufacture of trichlorosilane by reduction of tetrachlorosilane in
       fluidized bed)
     10025-78-2P, Trichlorosilane
IT
     RL: IMF (Industrial manufacture); PREP (Preparation)
        (manufacture of trichlorosilane by reduction of tetrachlorosilane in
fluidized
       bed)
IT
     7440-21-3, Silicon, reactions
     RL: PEP (Physical, engineering or chemical process); RCT
     (Reactant); TEM (Technical or engineered material use); PROC
     (Process); RACT (Reactant or reagent); USES (Uses)
        (in manufacture of trichlorosilane by reduction of tetrachlorosilane in
        fluidized bed)
     7440-21-3 CAPLUS
RN
    Silicon (7CI, 8CI, 9CI) (CA INDEX NAME)
CN
Si
IT
     10025-78-2P, Trichlorosilane
     RL: IMF (Industrial manufacture); PREP (Preparation)
        (manufacture of trichlorosilane by reduction of tetrachlorosilane in
fluidized
       bed)
RN
     10025-78-2 CAPLUS
     Silane, trichloro- (8CI, 9CI) (CA INDEX NAME)
CN
   Cl
cl-sih-cl
L75 ANSWER 4 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                        1994:424569 CAPLUS
DOCUMENT NUMBER:
                        121:24569
TITLE:
                        Fine contact hole etching in magneto-microwave
                        plasma
AUTHOR(S):
                        Miyakawa, Yasuhiro; Hashimoto, Jun; Ikegami, Naokatsu;
                        Matsui, Takayuki; Kanamori, Jun
CORPORATE SOURCE:
                        VLSI R and D Cent., Oki. Electr. Ind. Co., Ltd.,
```

```
Hachioji, 193, Japan
SOURCE:
                         Japanese Journal of Applied Physics, Part 1: Regular
                         Papers, Short Notes & Review Papers (1994), 33(4B),
                         2145-50
                         CODEN: JAPNDE; ISSN: 0021-4922
                         Journal
DOCUMENT TYPE:
                         English
LANGUAGE:
    Characteristics of fine contact hole etching have been investigated in
    hydro\mbox{-fluorocarbon} magneto-microwave plasma focusing on the z
     component of the gradient of magnetic field at 0.0875 T (dB/dz) and
    peak-to-peak voltage of RF bias (Vpp) as parameters. Decrease of dB/dz
    drastically decreases the etch rate of borophosphosilicate glass (BPSG),
     critical dimension loss (defined as diameter of the top of contact hole minus
    diameter of the bottom of resist) and selectivity over heavily doped n-type
    polycryst. silicon (n+ poly Si) and resist in fine contact holes. The
     changes of etching characteristics are correlated with neither F/C ratio
    nor Cls spectrum of deposited film, but with deposition rate in the region
    of high Vpp, which presumably reflects the change of incident CFm+ ion
     species with dB/dz.
    76-11 (Electric Phenomena)
CC
     Section cross-reference(s): 67
     silicon etching magneto microwave plasma; trifluoromethane
ST
     dichloromethane etching borophosphosilicate glass resist
IT
    Resists
        (etching of, with magneto-microwave plasma of fluorocarbons,
        comparison of, with silicon)
TΤ
    Etching
        (of silico, with magneto-microwave plasma of fluorocarbons)
IT
    Glass, oxide
    RL: RCT (Reactant); RACT (Reactant or reagent)
        (borophosphosilicate, etching of, with magneto-microwave
       plasma of fluorocarbons, comparison of, with silicon)
IT
     7440-21-3, Silicon, reactions
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (etching of, in magneto-microwave plasma of fluorocarbons)
IT
     38192-99-3P
     RL: FORM (Formation, nonpreparative); PREP (Preparation)
        (formation of, in magneto-microwave plasma etching of silicon
        using fluorocarbons)
IT
    75-10-5, Difluoromethane
                                75-46-7, Trifluoromethane
     RL: USES (Uses)
        (magneto-microwave plasma from, in etching of silicon)
IT
     18851-76-8
                  33412-11-2 54250-40-7
    RL: USES (Uses)
        (role of, in magneto-microwave plasma etching of silicon)
IT
     7440-21-3, Silicon, reactions
    RL: RCT (Reactant); RACT (Reactant or reagent)
        (etching of, in magneto-microwave plasma of fluorocarbons)
RN
     7440-21-3 CAPLUS
     Silicon (7CI, 8CI, 9CI) (CA INDEX NAME)
CN
Si
IT
     38192-99-3P
    RL: FORM (Formation, nonpreparative); PREP (Preparation)
        (formation of, in magneto-microwave plasma etching of silicon
        using fluorocarbons)
    38192-99-3 CAPLUS
RN
```

CN Silylium, trifluoro- (9CI) (CA INDEX NAME)

L75 ANSWER 5 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1989:585475 CAPLUS

DOCUMENT NUMBER: 111:185475

TITLE: Highly selective etching of silicon nitride (Si3N4) to silicon dioxide employing fluorine and chlorine atoms

generated by microwave discharge

AUTHOR(S): Suto, S.; Hayasaka, N.; Okano, H.; Horiike, Y.

CORPORATE SOURCE: VLSI Res. Cent., Toshiba Corp., Kawasaki, 210, Japan SOURCE: Journal of the Electrochemical Society (1989), 136(7),

2032-4

CODEN: JESOAN; ISSN: 0013-4651

DOCUMENT TYPE: Journal LANGUAGE: English

AB Highly selective etching of Si3N4 over SiO2 was investigated employing F and Cl atoms generated by the microwave discharge of an NF3 + Cl2 mixture F atoms alone react spontaneously with both Si3N4 and SiO2, leading to insufficient Si3N4/SiO2 selectivity. By adding Cl2 to NF3, most of the F atoms are rapidly converted to interhalogen FCl by a titration reaction with Cl2 in the gas phase. The resultant FCl mols. etch Si3N4 as well as Si, but do not react with SiO2 without any radiation assistance. As a result, infinite Si3N4/SiO2 selectivity has been achieved. The faster etching for Si3N4 is attributed to a lower ionicity in the chemical bond state for Si3N4 than that for SiO2.

CC 76-11 (Electric Phenomena)

Section cross-reference(s): 67

IT 7440-21-3, Silicon, reactions

RL: RCT (Reactant); RACT (Reactant or reagent) (etching of, by chlorine and fluorine atoms)

IT 14049-36-6P 18356-71-3P, Dichlorodifluorosilane

RL: FORM (Formation, nonpreparative); PREP (Preparation)

(formation of, in nitrogen trifluoride-chlorine etching of silicon nitride and silica)

IT 7440-21-3, Silicon, reactions

RL: RCT (Reactant); RACT (Reactant or reagent)

(etching of, by chlorine and fluorine atoms)

RN 7440-21-3 CAPLUS

CN Silicon (7CI, 8CI, 9CI) (CA INDEX NAME)

Si

IT 14049-36-6P 18356-71-3P, Dichlorodifluorosilane

RL: FORM (Formation, nonpreparative); PREP (Preparation)

(formation of, in nitrogen trifluoride-chlorine etching of silicon nitride and silica)

RN 14049-36-6 CAPLUS

CN Silane, chlorotrifluoro- (6CI, 7CI, 8CI, 9CI) (CA INDEX NAME)

RN 18356-71-3 CAPLUS

CN Silane, dichlorodifluoro- (6CI, 7CI, 8CI, 9CI) (CA INDEX NAME)

L75 ANSWER 6 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1988:56161 CAPLUS

DOCUMENT NUMBER: 108:56161

TITLE: Ab initio study of fluorinated silylboranes. 2
AUTHOR(S): Bock, C. W.; Trachtman, M.; Mains, Gilbert J.
CORPORATE SOURCE: Philadelphia Coll. Text. Sci., Philadelphia, PA,

19144, USA

SOURCE: Journal of Physical Chemistry (1988), 92(2), 294-9

CODEN: JPCHAX; ISSN: 0022-3654

DOCUMENT TYPE: Journal LANGUAGE: English

The reactions of singlet silylenes, H2Si and F2Si, with fluoroborane, FBH2, have been studied by ab initio MO methods using 3-21G and 6-31G\*(5D) basis sets. The effects of electron correlation at selected geometries were determined by Moller-Plesset perturbation theory. The reactions of H2Si with FBH2, leading to FH2SiBH2 by F atom transfer and to H3SiBHF by H atom transfer, proceed without the formation of an adduct or transition state. The reactions of F2Si with FBH2, leading to F3SiBH2 by F atom transfer and to HF2SiBH2 by H atom transfer, proceed with the formation of adducts (in the former case as a novel bridged structure) and transition states. In certain reactions F2Si behaves as a Lewis acid and in others as a Lewis base. The F atom transfer reaction has a 3.1 kcal/mol reaction barrier at the MP4SDQ/6-31G\* level and the H atom transfer reaction is found to have a 7.6 kcal/mol barrier at the same level. The structures of the fluorinated silylborane products as well as the adducts and transition states are given. The structure of perfluorosilylborane is presented and shown to be in excellent agreement with the structure determined by microwave spectroscopy.

CC 29-4 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 22

IT 19091-19-1P 111718-87-7P 111718-88-8P

111718-89-9P 111718-90-2P

RL: FORM (Formation, nonpreparative); PREP (Preparation) (formation of, from reaction of silylene with fluoroborane, MO in relation to)

IT 13825-90-6, Silylene 13966-66-0, Difluorosilylene

RL: RCT (Reactant); RACT (Reactant or reagent)

(reaction of, with fluoroborane, MO in relation to)

IT 19091-19-1P 111718-87-7P 111718-88-8P

111718-89-9P 111718-90-2P

RL: FORM (Formation, nonpreparative); PREP (Preparation) (formation of, from reaction of silylene with fluoroborane, MO in relation to) 19091-19-1 CAPLUS RNBorane, difluoro(trifluorosilyl) - (8CI, 9CI) (CA INDEX NAME) CNF-B-SiF3 RN 111718-87-7 CAPLUS CN Borane, (trifluorosilyl) - (9CI) (CA INDEX NAME) F-si-BH2 F RN111718-88-8 CAPLUS Borane, (difluorosily1)fluoro- (9CI) (CA INDEX NAME) F-SiH-BH-F 111718-89-9 CAPLUS RN CN Borane, (fluorosily1) - (9CI) (CA INDEX NAME)  $H_2B-SiH_2-F$ RN111718-90-2 CAPLUS Borane, fluorosilyl- (9CI) (CA INDEX NAME) F-BH-SiH3 13825-90-6, Silylene RL: RCT (Reactant); RACT (Reactant or reagent) (reaction of, with fluoroborane, MO in relation to) RN 13825-90-6 CAPLUS Silylene (8CI, 9CI) (CA INDEX NAME) CN  $SiH_2$ 

L75 ANSWER 7 OF 7 CAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1985:510678 CAPLUS

DOCUMENT NUMBER: 103:110678

```
TITLE:
                         Reaction of atomic fluorine with silicon
AUTHOR(S):
                         Ninomiya, Ken; Suzuki, Keizo; Nishimatsu, Shiqeru;
                         Okada, Osami
CORPORATE SOURCE:
                         Cent. Res. Lab., Hitachi, Ltd., Kokubunji, 185, Japan
SOURCE:
                         Journal of Applied Physics (1985), 58(3), 1177-82
                         CODEN: JAPIAU; ISSN: 0021-8979
DOCUMENT TYPE:
                         Journal
LANGUAGE:
                         English
     The etch rate of Si with F atoms was measured by the use of F2
     microwave plasma at discharge pressures between 2.7 + 10-2
     and 17 Pa. F atom concentration in the plasma was determined over the same
pressure
     range by both gas-phase titration and actinometry using Ar gas. A Si surface
     etched at 1.0 + 10-1, 5.3 + 10-1, 1.3, and 5.3 Pa was analyzed
     with XPS without exposing the surface to room air. A linear relation was
     obtained between the Si etch rate and the F atom concentration at discharge
     pressures between 2.7 + 10-2 and 2.7 Pa. The reaction probability
     of F atoms with Si to yield SiF4 was determined from the linear relation to be
     0.1 for a Si surface at .apprx.300 K. When the discharge pressure was
     >1.3 Pa, the surface became rather strongly oxidized by O atoms resulting
     from residual gases. This surface oxidation results in a slight saturation of
the
     Si etch rate at .apprx.10 Pa.
     67-3 (Catalysis, Reaction Kinetics, and Inorganic Reaction Mechanisms)
CC
     Section cross-reference(s): 56
IT
     Sputtering
        (etching, of silicon by fluorine microwave)
IT
     Etching
     Kinetics of etching
        (sputter, of silicon by fluorine microwave)
TT
     7440-21-3, reactions
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (etching of, by fluorine atoms, kinetics of)
     7783-61-1P
IT
     RL: FORM (Formation, nonpreparative); PREP (Preparation)
        (formation of, from silicon etching by fluorine microwave
        plasma, probability of)
     7782-41-4, reactions
TТ
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (microwave plasma, etching kinetics of silicon by)
TT
     7440-21-3, reactions
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (etching of, by fluorine atoms, kinetics of)
     7440-21-3 CAPLUS
RN
     Silicon (7CI, 8CI, 9CI)
                             (CA INDEX NAME)
CN
Si
IT
     7783-61-1P
     RL: FORM (Formation, nonpreparative); PREP (Preparation)
        (formation of, from silicon etching by fluorine microwave
        plasma, probability of)
     7783-61-1 CAPLUS
RN
     Silane, tetrafluoro- (9CI) (CA INDEX NAME)
CN
```

## AUTHOR SEARCH

=> file caplus

FILE 'CAPLUS' ENTERED AT 17:54:02 ON 27 APR 2006 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS.
COPYRIGHT (C) 2006 AMERICAN CHEMICAL SOCIETY (ACS)

Copyright of the articles to which records in this database refer is held by the publishers listed in the PUBLISHER (PB) field (available for records published or updated in Chemical Abstracts after December 26, 1996), unless otherwise indicated in the original publications. The CA Lexicon is the copyrighted intellectual property of the American Chemical Society and is provided to assist you in searching databases on STN. Any dissemination, distribution, copying, or storing of this information, without the prior written consent of CAS, is strictly prohibited.

FILE COVERS 1907 - 27 Apr 2006 VOL 144 ISS 18 FILE LAST UPDATED: 26 Apr 2006 (20060426/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply. They are available for your review at:

http://www.cas.org/infopolicy.html

'OBI' IS DEFAULT SEARCH FIELD FOR 'CAPLUS' FILE

=> d stat que L65

L24 110513 SEA FILE=CAPLUS ABB=ON PLU=ON ?MICROWAV?/BI
L25 35 SEA FILE=CAPLUS ABB=ON PLU=ON M/OBI(1W)WAVE/BI
L64 651 SEA FILE=CAPLUS ABB=ON PLU=ON AUNER N?/AU
L65 4 SEA FILE=CAPLUS ABB=ON PLU=ON L64 AND (L24 OR L25)

=> d stat que L70

L64 651 SEA FILE=CAPLUS ABB=ON PLU=ON AUNER N?/AU

L69 657892 SEA FILE=CAPLUS ABB=ON PLU=ON RADIA?/OBI OR IRRADIA?/OBI

L70 6 SEA FILE=CAPLUS ABB=ON PLU=ON L69 AND L64

=> d stat que L72

L64 651 SEA FILE=CAPLUS ABB=ON PLU=ON AUNER N?/AU L71 1682 SEA FILE=CAPLUS ABB=ON PLU=ON HALOSILANE/BI L72 15 SEA FILE=CAPLUS ABB=ON PLU=ON L71 AND L64

=> s L65 or L70 or L72

L76 22 L65 OR L70 OR L72

=> d ibib abs hitind L76 1-22

L76 ANSWER 1 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

2004:762295 CAPLUS

DOCUMENT NUMBER:

143:86476

TITLE:

Investigation of silicone-modified photocatalytic TiO2 formation by solid-liquid reaction and its structural

changes under irradiation

AUTHOR (S):

Nakabayashi, Akira

CORPORATE SOURCE:

Performance Chemicals R+D Department, Asahi Kasei Corporation, Kawasaki-ku, Kanagawa, 210-0863, Japan SOURCE: Organosilicon Chemistry V: From Molecules to

Materials, [Scientific Contributions presented at the European Silicon Days], 1st, Munich, Germany, Sept., 2001 (2003), Meeting Date 2001, 819-825.

Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH & Co. KGaA: Weinheim, Germany.

CODEN: 69FVR6; ISBN: 3-527-30670-6

DOCUMENT TYPE: Conference LANGUAGE: English

AB The kinetic study of the solid-liquid reaction between photocatalytic titanium dioxide (photo-TiO2) and H-siloxane was investigated. The results showed that the solid-liquid reaction was inhibited in the presence of water, alc., ether, or other polar mols., and supported its characterization as a dehydrogenation condensation reaction. synthesized silicone-modified photo-TiO2 by the solid-liquid reaction was initially hydrophobic, but became super-hydrophilic after irradiation by BLB light. Both ESR and Si-NMR studies suggested that this effect was caused by the photocatalytic oxidation of the silicone present on the photo-TiO2.

74-1 (Radiation Chemistry, Photochemistry, and Photographic and Other Reprographic Processes)

Section cross-reference(s): 67

REFERENCE COUNT: THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS 2

RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 2 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2004:762278 CAPLUS

DOCUMENT NUMBER: 142:464885

TITLE: Oil-bleeding properties of self-lubricating liquid

silicone rubbers

AUTHOR (S): Pohmer, Klaus

CORPORATE SOURCE: Burghausen Plant, Elastomers Business Unit, Rubber

> Fabricators Business Team, Automotive Rubber Market Segment, Wacker-Chemie GmbH, Burghausen, D-84480,

Germany

SOURCE: Organosilicon Chemistry V: From Molecules to

Materials, [Scientific Contributions presented at the European Silicon Days], 1st, Munich, Germany, Sept., 2001 (2003), Meeting Date 2001, 678-688. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH & Co. KGaA: Weinheim, Germany.

CODEN: 69FVR6; ISBN: 3-527-30670-6

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

A review. Liquid silicone rubber accounts for only a thousandth of the world's total rubber production, and is thus a specialty among rubber types. Nevertheless, LR products boast a large number of applications in many different fields. There is a particularly high demand for LR products in the automotive sector, where they are highly valued because of their low-temperature flexibility and thermal stability. Applications include radiator gaskets, exhaust pipe suspension elements, O-rings, seals and membranes, and insulating coverings for spark plugs. It has become standard practice to use weather packs made of special silicone rubber grades for sealing cable connectors for wiring harnesses. These silicone rubbers contain a silicone fluid which is incompatible with rubber and bleeds or exudes slowly after the product has cured.

CC 39-0 (Synthetic Elastomers and Natural Rubber)

IT Radiators

> (gaskets; oil-bleeding properties of self-lubricating liquid silicone rubbers and their applications)

Gaskets IT

```
(radiator; oil-bleeding properties of self-lubricating liquid
        silicone rubbers and their applications)
                               THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS
REFERENCE COUNT:
                         18
                               RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT
L76 ANSWER 3 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         2004:762232 CAPLUS
                         142:156049
DOCUMENT NUMBER:
                         Intensification of unsaturated organomagnesium
TITLE:
                         chloride production reaction
                         Zhun, Vladimir; Zhun, Alla; Chernyshev, Evgenii
AUTHOR (S):
                         Federal State Unitary Enterprise State Research
CORPORATE SOURCE:
                         Institute for Chemistry and Technology of
                         Organoelement Compounds, Moscow, 111123, Russia
                         Organosilicon Chemistry V: From Molecules to
SOURCE:
                         Materials, [Scientific Contributions presented at the
                         European Silicon Days], 1st, Munich, Germany, Sept.,
                         2001 (2003), Meeting Date 2001, 360-362. Editor(s):
                         Auner, Norbert; Weis, Johann. Wiley-VCH
                         Verlag GmbH & Co. KGaA: Weinheim, Germany.
                         CODEN: 69FVR6; ISBN: 3-527-30670-6
DOCUMENT TYPE:
                         Conference
LANGUAGE:
                         English
                         CASREACT 142:156049
OTHER SOURCE(S):
     The efficiency of the effect of ultrasound irradiation on the reaction mixture
     for vinyl- and phenylchlorosilane synthesis is determined by ultrasound
     (USI) frequency as well as by the exposure time and the origin of starting
     organo halide. In the case of vinylmagnesium chloride, the formation
     period of the major reaction product under continuous USI exposure
     shortened 2.3-fold. When USI affected the synthesis during half the
     reaction period, the latter duration shortened by 1.4 times. In the case
     of phenylmagnesium chloride the process period also shortened by 2 and 1.2
     times resp. for irradiation times that were 100 and 50 % of the reaction time.
     29-6 (Organometallic and Organometalloidal Compounds)
CC
     organo magnesium chloride prepn ultrasound irradn; magnesium
ST
     reaction vinyl phenyl chloride ultrasound irradn
     intensification; vinyl phenyl chloro silane prepn
     Grignard reaction
IT
     Sound and Ultrasound
        (intensification of unsatd. organomagnesium chloride production under
        ultrasound irradiation in preparation of vinyl- and
        phenylchlorosilanes)
TТ
     100-59-4, Phenylmagnesium chloride 3536-96-7, Vinylmagnesium chloride
     RL: FMU (Formation, unclassified); RCT (Reactant); FORM (Formation,
     nonpreparative); RACT (Reactant or reagent)
        (intensification of unsatd. organomagnesium chloride production under
        ultrasound irradiation in preparation of vinyl- and
        phenylchlorosilanes)
                                          108-90-7, Phenyl chloride, reactions
TΤ
     75-01-4, Vinyl chloride, reactions
     RL: RCT (Reactant); RACT (Reactant or reagent)
        (intensification of unsatd. organomagnesium chloride production under
        ultrasound irradiation in preparation of vinyl- and
        phenylchlorosilanes)
TΤ
     754-05-2P, Trimethylvinylsilane
                                       768-32-1P, Trimethylphenylsilane
     RL: SPN (Synthetic preparation); PREP (Preparation)
        (intensification of unsatd. organomagnesium chloride production under
        ultrasound irradiation in preparation of vinyl- and
```

THERE ARE 4 CITED REFERENCES AVAILABLE FOR THIS

phenylchlorosilanes)

REFERENCE COUNT:

## RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 4 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2004:762195 CAPLUS

DOCUMENT NUMBER: 142:156045

TITLE: Synthesis of a highly enantiomerically enriched

silyllithium compound

AUTHOR(S): Auer, Dominik; Hoernig, Jan; Strohmann, Carsten CORPORATE SOURCE: Institut fuer Anorganische Chemie, Universitaet

Wuerzburg, Wuerzburg, D-97074, Germany

SOURCE: Organosilicon Chemistry V: From Molecules to

Materials, [Scientific Contributions presented at the European Silicon Days], 1st, Munich, Germany, Sept., 2001 (2003), Meeting Date 2001, 167-170. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH & Co. KGaA: Weinheim, Germany.

CODEN: 69FVR6; ISBN: 3-527-30670-6

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

AB The highly enantiomerically enriched silyllithium compound lithiomethylphenyl(1-piperidinylmethyl)silane reacts stereospecifically with chlorosilanes, but over a period of several hours slow racemization in solution at room temperature occurs, which can be suppressed by a metathesis reaction with [Mg(THF)4]Br2. Quantum chemical calcns. (B3LYP) of solvated model systems allow an assessment of possible intermediates during the racemization process. The exptl., but not the theor., results comprise a

CC 29-6 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 22

IT Silanes

RL: RCT (Reactant); RACT (Reactant or reagent)

(halosilanes, chloro; synthesis of highly enantiomerically

enriched silyllithium compound, reactions with chlorosilanes and exptl.

and theor. studies of racemization)

REFERENCE COUNT: 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 5 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2004:762190 CAPLUS

DOCUMENT NUMBER: 142:114151

TITLE: The conformation preference of the methyl group in

1-methyl-1-silacyclohexane

AUTHOR(S): Arnason, Ingvar; Kvaran, Agust; Jonsdottir, Sigridur;

Gudnason, Palmar I.; Oberhammer, Heinz

CORPORATE SOURCE: Science Institute, University of Iceland, Reykjavik,

IS-107, Iceland

SOURCE: Organosilicon Chemistry V: From Molecules to

Materials, [Scientific Contributions presented at the European Silicon Days], 1st, Munich, Germany, Sept., 2001 (2003), Meeting Date 2001, 135-138. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH & Co. KGaA: Weinheim, Germany.

CODEN: 69FVR6; ISBN: 3-527-30670-6

DOCUMENT TYPE: Conference LANGUAGE: English

AB The conformational equilibrium of the title compound was studied exptl. in the gas phase by gas electron diffraction and in solution at low temps. by 13C NMR, and theor. by quantum chemical (HF/6-31G\*, MP2/6-31G\* and B3LYP/6-31G\*) calcns. Both exptl. methods result in a preference of the equatorial position of the Me group, 68(7)% in the gas phase at 298 K and 74(1)% in

```
solution at 110 K. The calcns. predict 66% equatorial conformer at room
temperature
```

CC 29-6 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 22, 65

TTConformation

Hartree-Fock method

MP2 (second-order Moller-Plesset method)

Methyl group

Radial distribution function

(NMR, electron diffraction and quantum chemical studies of conformation preference of Me group in 1-methylsilacyclohexane)

REFERENCE COUNT:

THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 6 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER:

2003:837093 CAPLUS

DOCUMENT NUMBER:

139:307891

TITLE:

Process for producing halosilanes from

silicon and mixtures of halogens, hydrogen and/or

halogen-containing compounds by impinging

microwave energy

INVENTOR(S):

Auner, Norbert

PATENT ASSIGNEE(S):

Wacker-Chemie G.m.b.H., Germany; Dow Corning

Corporation

SOURCE:

PCT Int. Appl., 17 pp.

CODEN: PIXXD2

DOCUMENT TYPE:

Patent

LANGUAGE:

German

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PAT							KIND DATE				APPLICATION NO.						DATE			
	WO 2003087107					A2 20031023			WO 2003-DE1270						20030415					
WO	2003087107																			
	W :												CA,							
													IS,							
													MK,							
		NO,	ΝZ,	OM,	PH,	PL,	RO,	RU,	SD,	SG,	SL,	ΤJ,	TM,	TN,	TT,	TZ,	UA,			
		UG,	US,	UΖ,	VN,	YU,	ZA,	ZM,	ZW											
	RW:	GH,	GM,	KE,	LS,	MW,	ΜZ,	SD,	SL,	SZ,	TZ,	ŪĠ,	ZM,	ZW,	AM,	ΑZ,	BY,			
		KG,	ΚZ,	MD,	RU,	TJ,	TM,	AT,	BE,	BG,	CH,	CY,	CZ,	DE,	DK,	EE,	ES,			
		FI,	FR,	GB,	GR,	HU,	ΙE,	IT,	LU,	MC,	NL,	PT,	RO,	SE,	SI,	SK,	TR,			
													MR,							
DE	DE 10222728								DE 2002-10222728						20020523					
DE	DE 10227041						2003	1106	]	DE 2	2002-10227041 20020					0020	617			
									AU 2003-236776						20030415					
						A2 20050112				EP 2003-735264						20030415				
	R:	AT.											LU,							
													CZ,							
US	US 2005143592					A1 20050630				US 2003-510583						20030415				
									CN 2003-808605											
									JP 2003-584063											
	IORITY APPLN. INFO.:												7139							
KIOKIII				• •									2728			0020				
•	·												7041							
													70			0030				
THER SO	HER SOURCE(S):						CASREACT 139:307891; MARPAT 139:307891													

CASREACT 139:307891; MARPAT 139:307891

AB Halogen-containing silanes RaHbSiXc [R = (un)substituted C1-10 alkyl or aryl in which ≥1 C atoms can be replaced by CO, CO2, O, S, SO, SO2, NH

or NR', where R' = (un) substituted C1-20 alkyl; X = F, Cl, Br; a = 0-3, b = 0-3, c = 1-4, and a + b + c = 4] are prepared by reaction of Si in presence of microwave energy with a gaseous atmospheric of mixts. of elements or compds. selected from among halogens, halogens and organohalogen compds., halogens and hydrogen, halogens and hydrogen halides, organohalogen compds. (alkyl or aryl halides, preferably MeCl), organohalogen compds. and hydrogen, organohalogen compds. and hydrogen halide, hydrogen halides, fluorosilanes and hydrogen, fluorosilanes and hydrogen halides, hydrogen-containing chlorosilanes and hydrogen, hydrogen-containing chlorosilanes and hydrogen halides, organohalosilanes and hydrogen, organohalosilanes and hydrogen halides or hydrocarbons (preferably methane or ethane) and hydrogen halides. Elemental Si used may be crystalline or amorphous, or mixts. of both, or in the form of a silicon alloy, preferably ferrosilicon, and the process may be carried out in presence of a metal or metal-containing catalyst or promotor, preferably Cu. This process uses much less energy and is thus more economical for production of halosilanes than prior art. In the example given, reaction of 98.5% ferrosilicon with a 1:1 gaseous mixture of MeCl and Ar with microwave irradiation gave 6.4% MeSiCl3, 82% Me2SiCl2 and 11.6% Me3SiCl.

- IC ICM C07F007-02
- CC 29-6 (Organometallic and Organometalloidal Compounds)
   Section cross-reference(s): 45, 49, 78
- ST halosilane prepn process microwave irradn
- TT Silanes

RL: IMF (Industrial manufacture); RCT (Reactant); SPN (Synthetic preparation); PREP (Preparation); RACT (Reactant or reagent) (chloro; process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Silanes

RL: IMF (Industrial manufacture); RCT (Reactant); SPN (Synthetic preparation); PREP (Preparation); RACT (Reactant or reagent) (fluoro; process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Silanes

RL: IMF (Industrial manufacture); SPN (Synthetic preparation); PREP (Preparation)

(halosilanes; process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Microwave

(irradiation; process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT Halides

RL: RCT (Reactant); RACT (Reactant or reagent)
 (organic; process for preparation of halosilanes from silicon and
 mixts. of halogens, hydrogen and/or halogen-containing compds. by using
 microwave irradiation)

IT Hydrogen halides

RL: RCT (Reactant); RACT (Reactant or reagent)
 (process for preparation of halosilanes from silicon and mixts. of
 halogens, hydrogen and/or halogen-containing compds. by using
 microwave irradiation)

IT 75-79-6P, Trichloro(methyl)silane

RL: BYP (Byproduct); SPN (Synthetic preparation); PREP (Preparation) (process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using

## microwave irradiation)

IT 7440-50-8, Copper, uses

RL: CAT (Catalyst use); USES (Uses)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT 75-78-5P, Dichloro (dimethyl) silane

RL: IMF (Industrial manufacture); SPN (Synthetic preparation); PREP (Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

TT 74-82-8, Methane, reactions 74-84-0, Ethane, reactions 74-87-3, Methyl
 chloride, reactions 1333-74-0, Hydrogen, reactions 7440-21-3, Silicon,
 reactions 7647-01-0, Hydrogen chloride, reactions 7664-39-3, Hydrogen
 fluoride, reactions 7783-61-1, Silicon tetrafluoride 8049-17-0,
 Ferrosilicon

RL: RCT (Reactant); RACT (Reactant or reagent)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

IT 75-77-4P, Chloro(trimethyl)silane, preparation

RL: SPN (Synthetic preparation); PREP (Preparation)

(process for preparation of halosilanes from silicon and mixts. of halogens, hydrogen and/or halogen-containing compds. by using microwave irradiation)

L76 ANSWER 7 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2003:570911 CAPLUS

DOCUMENT NUMBER: 139:103149

TITLE: Production of amorphous silicon and/or

organohalosilanes

INVENTOR(S): Auner, Norbert

PATENT ASSIGNEE(S): Wacker-Chemie G.m.b.H., Germany; Dow Corning

Corporation

SOURCE: PCT Int. Appl., 34 pp.

CODEN: PIXXD2

DOCUMENT TYPE: Patent LANGUAGE: German

FAMILY ACC. NUM. COUNT: 2

PATENT INFORMATION:

PATENT NO.					KIN	)	DATE		APPLICATION NO.						DATE			
WO 2003059815					A1 20030724			1	WO 2	003-1	DE11		20030117					
	W:	ΑE,	AG,	AL,	AM,	AU,	ΑZ,	BA,	BB,	BR,	BY,	ΒZ,	CA,	CN,	CO,	CR,	CU,	
		DM,	DZ,	EC,	GD,	GE,	GH,	GM,	HR,	ID,	IL,	IN,	IS,	JP,	ΚE,	KG,	ΚP,	
		KR,	KZ,	LC,	LK,	LR,	LS,	LT,	LV,	MA,	MD,	MG,	MK,	MN,	MW,	MX,	MZ,	
		NO,	NZ,	OM,	PH,	PL,	RO,	RU,	SD,	SG,	SL,	TJ,	TM,	TN,	TT,	TZ,	UA,	
		UG,	US,	UΖ,	VN,	YU,	ZA,	ZM,	ZW									
	RW:	GH,	GM,	KE,	LS,	MW,	MZ,	SD,	SL,	SZ,	TZ,	UG,	ZM,	ZW,	AM,	ΑZ,	BY,	
		KG,	ΚZ,	MD,	RU,	ТJ,	TM,	ΑT,	ΒE,	BG,	CH,	CY,	CZ,	DE,	DK,	EE,	ES,	
		FI,	FR,	GB,	GR,	HU,	IE,	ΙT,	LU,	MC,	NL,	PT,	SE,	SI,	SK,	TR,	BF,	
		ВJ,	CF,	CG,	CI,	CM,	GΑ,	GN,	GQ,	GW,	ML,	MR,	ΝE,	SN,	TD,	TG		
DE	DE 10217125				A1		20030731			DE 2	002-		20020417					
DE	E 10217124			A1		2003	1030		DE 2	002-		20020417						
DE	DE 10217126			A1	20031030				DE 2	002-		20020417						
DE	DE 10217140			<b>A</b> 1	20031030				DE 2	002-		20020417						
AU 2003206626				A1		20030730			AU 2	003-	20030117							
EP 1474361			<b>A</b> 1		20041110			EP 2	003-	20030117								

```
R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,
             IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK
     JP 2005514312
                          T2
                                20050519
                                            JP 2003-559926
     CN 1620404
                          Α
                                20050525
                                            CN 2003-802454
                                                                    20030117
     US 2005053540
                          A1
                                20050310
                                            US 2004-501369
                                                                    20040714
PRIORITY APPLN. INFO.:
                                            DE 2002-10201772
                                                                A 20020118
                                            DE 2002-10217124
                                                                Α
                                                                   20020417
                                            DE 2002-10217125
                                                                Α
                                                                   20020417
                                            DE 2002-10217126
                                                                Α
                                                                   20020417
                                            DE 2002-10217140
                                                                Α
                                                                   20020417
                                            WO 2003-DE116
                                                                W
                                                                   20030117
AΒ
     The invention relates to a method for producing amorphous Si and/or
     organohalosilanes. In a 1st embodiment of the method, a
     halosilane is reacted with a metal in an apolar solvent.
                                                               In a 2nd
     embodiment, the black amorphous Si is reacted with an organohalogen to
     form an organohalosilane. In a 3rd embodiment, amorphous Si is produced
     by reducing SiCl4 with a metal in an apolar solvent. In a 4th embodiment,
     amorphous Si is produced by reacting SiF4 with a metal. The method can be
     carried out by using an especially small amount of materials and/or energy,
and/or
     is characterized by an especially high versatility.
IC
     ICM C01B033-033
CC
     49-1 (Industrial Inorganic Chemicals)
IT
     Silanes
     RL: CPS (Chemical process); IMF (Industrial manufacture); PEP (Physical,
     engineering or chemical process); PREP (Preparation); PROC (Process)
        (halosilanes, organo-; production of amorphous silicon and/or
        organohalosilanes)
ΙT
     Microwave
        (in production of organohalosilanes)
REFERENCE COUNT:
                         4
                               THERE ARE 4 CITED REFERENCES AVAILABLE FOR THIS
                               RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT
L76 ANSWER 8 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN
ACCESSION NUMBER:
                         2003:91323
                                    CAPLUS
DOCUMENT NUMBER:
                         139:53069
TITLE:
                         Modeling SN2 nucleophilic substitution at silicon by
                         structural correlation with X-ray crystallography and
                         NMR spectroscopy
AUTHOR (S):
                         Bassindale, Alan R.; Parker, David J.; Taylor, Peter
                         G.; Auner, Norbert; Herrschaft, Bernhard
                         Department of Chemistry, Open University, Milton
CORPORATE SOURCE:
                         Keynes, MK7 6AA, UK
SOURCE:
                         Journal of Organometallic Chemistry (2003), 667(1-2),
                         66-72
                         CODEN: JORCAI; ISSN: 0022-328X
PUBLISHER:
                         Elsevier Science B.V.
DOCUMENT TYPE:
                         Journal
LANGUAGE:
                         English
OTHER SOURCE(S):
                         CASREACT 139:53069
     The x-ray crystal structures of four 1-(halodimethylsilylmethyl)-2-
     quinolinones were measured and used to model the reaction profile for
     nucleophilic substitution at Si. Similar structural correlations were
     performed in solution, the percentage Si-O bond formation being obtained from
     the 13C chemical shifts of the quinolinone carbons and the extent of
     pentacoordination from the 29Si chemical shift of the Si. Excellent
     agreement was obtained between the two methods confirming the validity of
     the NMR technique for structural correlation in solution
CC
     29-6 (Organometallic and Organometalloidal Compounds)
     Section cross-reference(s): 22, 75
```

Nwaonicha 10/510583 ΙT 59-31-4, 2-Quinolinone RL: RCT (Reactant); RACT (Reactant or reagent) (reaction with halosilanes and modeling of SN2 nucleophilic substitution at silicon by structural correlation with X-ray crystallog. and NMR of (halodimethylsilylmethyl)quinolinones) ΙT 996-50-9 RL: RCT (Reactant); RACT (Reactant or reagent) (reaction with quinolinone and halosilanes and modeling of SN2 nucleophilic substitution at silicon by structural correlation with X-ray crystallog. and NMR of (halodimethylsilylmethyl)quinolinones) THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS REFERENCE COUNT: 21 RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 9 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2000:349821 CAPLUS

DOCUMENT NUMBER: 133:123868

TITLE: Novel silyl-carbodiimide gels for the preparation of

Si/C/(N) ceramics

AUTHOR (S): Kroke, Edwin; Gabriel, Andreas O.; Kim, Dong Seok;

Riedel, Ralf

CORPORATE SOURCE: Fachgebiet Disperse Feststoffe Fachbereich

Materialwissenschaft Technische Universitat Darmstadt,

Darmstadt, D-64287, Germany

SOURCE: Organosilicon Chemistry IV: From Molecules to

Materials, [Lectures and Poster Contributions

presented at the Muechner Silicontage], 4th, Muechen,

Apr., 1998 (2000), Meeting Date 1998, 812-817.

Editor(s): Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH: Weinheim, Germany.

CODEN: 68ZMAL

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

A review and discussion, with 23 refs., of the use of silyl-carbodiimide gels for the preparation of Si/C/(N) ceramics. Examples from the authors work on reactions of chlorosilanes with stoichiometric amts. of bis(trimethylsilyl)carbodiimide are described. The sol-gel process based on alkoxysilanes has been used extensively to prepare oxide glasses and ceramics. Several attempts to apply analogous sol-gel synthesis routes to non-oxide materials were only partially successful. Recently we have found that several di- and trichlorosilanes like MeRSiCl2 (R = -H, -SiCl2Me, -CH2CH2SiCl2Me) or RSiCl3 (R = -H, -Cl, -Me, -Ph, -SiCl3, -CH2CH2SiCl3), and other silanes as well as silane mixts. react with bis(trimethylsilyl)carbodiimide (Me3Si-N=C=N-SiMe3) to form polymeric organosilicon gels. Usually no solvent is required and pyridine is used as a catalyst. The highly cross-linked gels are prepared at 20-60°C. In very few cases the sol-gel transition is reversible. Insol. colorless xerogels are obtained by evaporation of the liquid phase. Heat treatment transforms these polymers into ceramic materials in the ternary Si/C/(N) system.

57-0 (Ceramics)

Section cross-reference(s): 38

Silanes IT

RL: RCT (Reactant); RACT (Reactant or reagent)

(halosilanes, starting material; novel silyl-carbodiimide

gels for preparation of Si/C/(N) ceramics)

REFERENCE COUNT: THERE ARE 26 CITED REFERENCES AVAILABLE FOR THIS 26 RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 10 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2000:349782 CAPLUS DOCUMENT NUMBER: 133:266917

TITLE: Salen-silicon complexes - a new type of hexacoordinate

silicon

AUTHOR (S): Haberecht, Jorg; Mucha, Frank; Bohme, Uwe; Roewer,

CORPORATE SOURCE: Institut fur Anorganische Chemie Technische

Universitat Bergakademie Freiberg, Freiberg, D-09596,

SOURCE: Organosilicon Chemistry IV: From Molecules to

Materials, [Lectures and Poster Contributions

presented at the Muechner Silicontage], 4th, Muechen,

Apr., 1998 (2000), Meeting Date 1998, 500-504.

Editor(s): Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH: Weinheim, Germany.

CODEN: 68ZMAL Conference

DOCUMENT TYPE: LANGUAGE: English

The reaction of tetradentate azomethine ligands H2salen\*

[N,N'-ethylene-bis(2-hydroxyacetophenoneimine)] or H2salen.dbldag.

[N,N'-ethylene-bis(3,5-di-tert-butyl-salicylideneimine)] with

chlorosilanes produces Si compds. with hexacoordinated Si (salen)SiXY (X = Cl; Y = H, Cl, CH3, C6H5). Both ligands X and Y can be exchanged for F.

The crystal structure anal. of (salen\*)SiF2 reveals the truly

hexacoordination of the Si atom. The chloro compds. (salen\*)SiCl2 undergo Wurtz-type coupling reactions leading to oligosilanes with hypervalent Si. Coupling of (salen\*)SiCl2 with acetylides creates compds. with an

Si-C.tplbond.C-Si backbone.

29-6 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 75, 77, 78

IT Silanes

RL: RCT (Reactant); RACT (Reactant or reagent)

(halosilanes, chloro; reaction with

ethylenebishydroxyacetophenoneimine to give salen complex containing

hexacoordinate silicon) REFERENCE COUNT: THERE ARE 12 CITED REFERENCES AVAILABLE FOR THIS

L76 ANSWER 11 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 2000:349735 CAPLUS

DOCUMENT NUMBER: 133:321933

Heteroaromatic-substituted silanes - synthesis, TITLE: lithium derivatives and anionic rearrangements

Baum, Claudia; Frenzel, Andrea; Klingebiel, Uwe; AUTHOR (S):

Neugebauer, Peter

Institut fur Anorganische Chemie, Georg-August-CORPORATE SOURCE:

Universitat, Gottingen, D-37077, Germany

Organosilicon Chemistry IV: From Molecules to SOURCE:

Materials, [Lectures and Poster Contributions

presented at the Muechner Silicontage], 4th, Muechen,

RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

Apr., 1998 (2000), Meeting Date 1998, 232-237. Editor(s): Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH: Weinheim, Germany.

CODEN: 68ZMAL

DOCUMENT TYPE: Conference

LANGUAGE: English

OTHER SOURCE(S): CASREACT 133:321933

GI

III

AB Pure and mixed substituted indolyl-, pyrrolyl-, and furanyl-silanes are formed in the reaction of heteroarom. compds. with Li heteroaryls and halosilanes, i.e., reaction 2-furanyllithium with SiF4 gave tetrakis(2-furanyl)silane. Chains of silyl-bridged mols. (I) were prepared as well. The crystal structure of a Li derivative (II) is presented and the 1,2-silyl group migration from N to C is proved. Formation of a 16-membered macrocycle (III) containing four indole mols. is described.

CC 29-6 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 27, 75

ST crystal structure furanylsilane indolylsilane lithium indolide; mol structure furanylsilane indolylsilane lithium indolide; indolylsilane prepn structure; pyrrolylsilane prepn; furanylsilane prepn structure; heteroarom substituted silane prepn anionic rearrangement; lithium deriv heteroarom substituted silane prepn; halosilane heteroaryllithium reaction heteroarom substituted silane prepn; indolyllithium prepn structure; phenyl mixed heteroarom silane prepn; macrocycle tetrasilatetraindolyl contg prepn; silyl shift indolylsilane deriv

IT Silanes

RL: RCT (Reactant); RACT (Reactant or reagent)

(halosilanes; reaction of heteroarom. compds. with Li alkyls and halosilanes in preparation of heteroarom.-substituted silanes)

REFERENCE COUNT: 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS

RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 12 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 2000:349713 CAPLUS

DOCUMENT NUMBER: 133:150612

TITLE: Sterically overloaded silanes, silylenes and disilenes

with supersilyl substituents tBu3Si

AUTHOR(S): Wiberg, Nils; Niedermayer, Wolfgang; Polborn, Kurt;

Noth, Heinrich; Knizek, Jorg; Fenske, Dieter; Baum,

Gerhard

CORPORATE SOURCE: Institut fur Anorganische Chemie, Ludwig-Maximilians-Universitat Munchen, Munchen, D-81377, Germany SOURCE: Organosilicon Chemistry IV: From Molecules to Materials, [Lectures and Poster Contributions presented at the Muechner Silicontage], 4th, Muechen, Apr., 1998 (2000), Meeting Date 1998, 93-97. Editor(s): Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH: Weinheim, Germany. CODEN: 68ZMAL DOCUMENT TYPE: Conference LANGUAGE: English OTHER SOURCE(S): CASREACT 133:150612 Silanes, tBu3SiSiX3 and (tBu3Si)2SiX2, with bulky supersilyl substituents are easily accessible by reaction of halosilanes (e.q., H2SiCl2, SiF4, MeSiHCl2) with tBu3SiNa. Their decomposition into silylenes and their transformation into their silanides as well as into a stable disilene with phenyl- and supersilyl-substituents are described. The constitutions of tBu3SiSiI3, (tBu3Si)2SiCl2 and tBu3SiPhSi:SiPhSitBu3 are solved by x-ray structure analyses. 29-6 (Organometallic and Organometalloidal Compounds) Section cross-reference(s): 75 silanide tritertbutyl reaction halosilane; silylene supersilyl substituent prepn; crystal structure tritertbutyl triiodo disilane dichlorodisilylsilane; mol structure tritertbutyl triiodo disilane dichlorodisilylsilane; disilane tritertbutyl triiodo prepn crystal structure; silane dichlorodisilyl prepn crystal structure; supersilyl substituent overloaded silane silylene disilene chem Silanes RL: SPN (Synthetic preparation); PREP (Preparation) (di-; silvlation of halosilanes by sodium tritertbutylsilanide to give disilanes) Silvlation IT (of halosilanes by sodium tritertbutylsilanide to give disilanes) 103349-41-3 IT RL: RCT (Reactant); RACT (Reactant or reagent) (reactions with halosilanes) REFERENCE COUNT: THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS 3 RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT L76 ANSWER 13 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1998:182171 CAPLUS DOCUMENT NUMBER: 128:233914 TITLE: Microporous thermal insulation: theory, properties, applications AUTHOR(S): Katzer, Hans; Weis, Johann Wacker-Chemie GmbH, Kempten, D-87437, Germany CORPORATE SOURCE: SOURCE: Organosilicon Chemistry III: From Molecules to Materials, [Muenchner Silicontage], 3rd, Munich, Apr., 1996 (1998), Meeting Date 1996, 682-690. Editor(s): Auner, Norbert; Weis, Johann. Wiley-VCH Verlag GmbH: Weinheim, Germany. CODEN: 65UHAS DOCUMENT TYPE: Conference; General Review LANGUAGE: English A review with 3 refs. The phys. requirements for a high performance

insulation material can be fulfilled with pressed mixts. consisting of fumed silica and opacifiers or with aerogels. No other com. available nonflammable system can compete with these, either by heat flow transferred through gases, or through solid-state transmission.

IR permeability of thermal radiation can be reduced with the addition of opacifiers. Since commencement of com. production at the beginning of the 1950s, the interest in microporous thermal insulation materials has grown continuously. Therefore, for example, aerogels are used in the insulation of lighting elements, refrigerators and water boilers. Products made from fumed silica are largely used as insulation for radiant heaters in glass ceramic hobs, in night storage heaters and in numerous industrial applications in high temperature areas.

CC 57-0 (Ceramics) IT IR radiation Opacifiers

Thermal insulators

(theory and properties and applications of microporous thermal insulation from pressed mixts. of fumed silica and opacifiers or

REFERENCE COUNT: THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 14 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1998:182144 CAPLUS

DOCUMENT NUMBER: 128:236633

TITLE: Localization phenomena of photogenerated charge

carriers in silicon structures: from organosilicon

compounds to bulk silicon

Wirschem, Thomas; Veprek, Stan AUTHOR(S):

Inst. Chem. Anorg. Mater., Tech. Univ. Munchen, Garching, D-85747, Germany CORPORATE SOURCE:

Organosilicon Chemistry III: From Molecules to SOURCE:

Materials, [Muenchner Silicontage], 3rd, Munich, Apr., 1996 (1998), Meeting Date 1996, 643-648. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH

Verlag GmbH: Weinheim, Germany.

CODEN: 65UHAS

DOCUMENT TYPE: Conference LANGUAGE: English

The luminescence properties of a variety of silicon structures are presented. The sizes range from simple organosilicon compds. over nanoand microcryst. silicon to bulk silicon. Time-resolved microwave absorption measurements have been used to show the importance of localization of the photogenerated charge carriers for an efficient luminescence in systems with reduced effective dimensionality of the Si matrix.

73-5 (Optical, Electron, and Mass Spectroscopy and Other Related Properties)

Section cross-reference(s): 57

REFERENCE COUNT: 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 15 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1998:181797 CAPLUS

DOCUMENT NUMBER: 128:230421

TITLE: Investigations of nucleophilic substitution at

silicon: an unprecedented equilibrium between an ionic

and covalent chlorosilane

Schar, D.; Belzner, J. AUTHOR(S):

Inst. Org. Chem., Georg-August-Univ., Gottingen, CORPORATE SOURCE:

D-37077, Germany

Organosilicon Chemistry III: From Molecules to SOURCE:

Materials, [Muenchner Silicontage], 3rd, Munich, Apr., 1996 (1998), Meeting Date 1996, 429-434. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH

Verlag GmbH: Weinheim, Germany.

CODEN: 65UHAS

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

AB A review with 6 refs. A series of halosilanes R2SiH(Hal) (R =

2-(Me2NCH2)C6H4) were prepared The influence of the leaving group ability
 of the halogen substituent, the polarity of the solvent, temperature, and
concentration

on the formation of intramol. coordinated silyl cations has been investigated.

CC 29-0 (Organometallic and Organometalloidal Compounds)

REFERENCE COUNT: 8 THERE ARE 8 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 16 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1998:181684 CAPLUS

DOCUMENT NUMBER: 128:204934

DOCUMENT TYPE:

LANGUAGE:

TITLE: On the reaction of (tBu2SnO)3 with

organochlorosilanes. Simple formation of

[(tBu2SnO)2(tBu2SiO)]

AUTHOR(S): Beckmann, Jens; Jurkschat, Klaus; Schollmeyer, Dieter

CORPORATE SOURCE: Fachber. Chem., Univ. Dortmund, Dortmund, D-44221,

Germany

SOURCE: Organosilicon Chemistry III: From Molecules to

Materials, [Muenchner Silicontage], 3rd, Munich, Apr., 1996 (1998), Meeting Date 1996, 403-406. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH

Verlag GmbH: Weinheim, Germany.

CODEN: 65UHAS Conference English

AB The reaction of (tBu2SnO)3 with tBu2SiCl2 gave [(tBu2SnO)2(tBu2SiO)] and tBu2Sn[OSi(tBu2)O]2SntBu2 (4) whereas treatment of (tBu2SnO)3 with

tBu2SiF2 afforded tBu2Sn[OSi(F)tBu2]2. The compds. were characterized by NMR spectroscopy, mass spectrometry, and in case of 4 also by x-ray anal.

CC 29-6 (Organometallic and Organometalloidal Compounds)

Section cross-reference(s): 75

ST crystal structure tetraoxadisiladistannacyclooctane; mol structure tetraoxadisiladistannacyclooctane; tetraoxadisiladistannacyclooctane tbutyl prepn structure; cyclization tristannatrioxane halosilane; silastannaoxacycloalkane prepn; stannasilaoxacycloalkane prepn

REFERENCE COUNT: 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 17 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1998:179492 CAPLUS

DOCUMENT NUMBER: 128:230406

TITLE: Novel synthetic approach to molybdenum-silicon

compounds: structures and reactivities

AUTHOR(S): Jutzi, Peter; Petri, Stefan H. A.

CORPORATE SOURCE: Fak. Chem., Univ. Bielefeld, Bielefeld, D-33615,

Germany

SOURCE: Organosilicon Chemistry III: From Molecules to

Materials, [Muenchner Silicontage], 3rd, Munich, Apr., 1996 (1998), Meeting Date 1996, 275-280. Editor(s):

Auner, Norbert; Weis, Johann. Wiley-VCH

Verlag GmbH: Weinheim, Germany.

CODEN: 65UHAS

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

A review with > 10 refs. For several reasons, complexes with a transition metal-silicon bond are of special interest. A new and very convenient synthesis of molybdenum-silicon compds. is presented. The complexes Cp2Mo(H)SiBr3 (1) and Cp2Mo(H)Si2Cl5 (2) are formed by simply stirring a solution of Cp2MoH2 in toluene in the presence of the corresponding halosilane. The x-ray crystal structure analyses reveal the shortest ever observed Mo-Si bond distances (1: 2.459(3) Å and 2: 2.4636(8)Å). Several other new Cp2Mo(H)SiR3 complexes are synthesized by the well-known reductive elimination/oxidative addition reaction starting from Cp2MoH2 and the corresponding hydridosilane. Some typical reactions of these compds. are presented.

29-0 (Organometallic and Organometalloidal Compounds)

REFERENCE COUNT: THERE ARE 24 CITED REFERENCES AVAILABLE FOR THIS 24 RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L76 ANSWER 18 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

1995:423282 CAPLUS ACCESSION NUMBER:

122:265418 DOCUMENT NUMBER:

Homo- and heterocyclic Si-O-systems rings and cages TITLE:

AUTHOR(S): Klingebiel, Uwe

Institut fur Anorganische Chemie, Georg-August-CORPORATE SOURCE: Universitat Gottingen, Gottingen, D-37077, Germany

Organosilicon Chem. (1994), 51-5. Editor(s):

SOURCE:

Auner, Norbert; Weis, Johann. VCH: Weinheim,

Germany. CODEN: 60NDAG

DOCUMENT TYPE: Conference; General Review

LANGUAGE: English

A review with 12 refs. Hydrolysis of chlorosilanes and subsequent condensation of the resulting silanols represent a very common way of preparing acyclic and cyclic siloxanes. Since the condensation happens spontaneously it is very difficult to control the ring size or to introduce other elements and units into these Si-O ring systems. The authors prepared functional silanols (Me3C)2Si(OH)X (X = OH, F, Cl, NH2), useful precursors for the stepwise synthesis of Si-O systems. These silanols do not readily self-condense due to the presence of bulky substituents. By forming the alkali metal derivs, and reacting them with halosilanes it is possible to build functionalized siloxane units of nearly any size, which can be used in ring-closure reactions. The x-ray structural anal. of the alkali metal derivs. provides some information about the reaction mechanism.

CC 29-0 (Organometallic and Organometalloidal Compounds)

L76 ANSWER 19 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1995:423273 CAPLUS

123:56762 DOCUMENT NUMBER:

Electroreductive formation of di- and polysilanes TITLE:

Hengge, E.; Jammegg, Ch. AUTHOR (S):

CORPORATE SOURCE: Institut fur Anorganische Chemie, Technische

Universitat Graz, Graz, A-8010, Austria

Organosilicon Chem. (1994), 27-9. Editor(s): SOURCE:

Auner, Norbert; Weis, Johann. VCH: Weinheim,

Germany.

CODEN: 60NDAG

DOCUMENT TYPE: Conference LANGUAGE: English

AB The electrochem. polymerization of halosilanes using a SiC anode is

35-7 (Chemistry of Synthetic High Polymers)

Section cross-reference(s): 72 polysilane electrochem prepn; electrochem polymn halosilane; ST silicon carbide anode electrochem polymn IT Anodes (electrochem. polymerization of halosilanes using SiC anode) Polymerization IT (electrochem., of halosilanes using SiC anode) Silanes IT RL: RCT (Reactant); RACT (Reactant or reagent) (halo, electrochem. polymerization of halosilanes using SiC anode) IT 409-21-2, Silicon carbide, uses RL: DEV (Device component use); USES (Uses) (electrochem. polymerization of halosilanes using SiC anode) L76 ANSWER 20 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1994:191783 CAPLUS DOCUMENT NUMBER: 120:191783 TITLE: Structural investigation of higher coordinated silicon compounds: model for nucleophilic substitution at silicon center AUTHOR (S): Auner, N.; Probst, R.; Hahn, F.; Herdtweck, CORPORATE SOURCE: Anorganisch-chemisches Institut der Technischen Universitaet Muenchen, Lichtenbergstr. 4, Garching bei Munchen, D-85747, Germany SOURCE: Journal of Organometallic Chemistry (1993), 459(1-2), CODEN: JORCAI; ISSN: 0022-328X DOCUMENT TYPE: Journal LANGUAGE: German OTHER SOURCE(S): CASREACT 120:191783 Silicon compds. substituted by 2-(dimethylaminomethyl)phenyl groups (C6H4CH2NMe2)nSiX4-n (X = Cl, H, organo group, n = 1-4) are available by the reaction of the appropriate chlorosilanes with 2-(dimethylaminomethyl)phenyllithium. A comparison of the 29Si NMR spectroscopic shifts  $\delta$  with the values obtained for corresponding Ph silanes shows that there is higher coordination of the silicon atom by  $N\rightarrow Si$  contacts, except for the silanes 11 (X = Cl; n = 3) and 12 (n = 4). X-ray crystal structure anal. confirms pentacoordination of the silicon atom in the dichlorosilanes 4 (X = C1; n = 2) and 5. For (C6H4CH2NMe2)3SiH (10), heptacoordination of the silicon atom is found in the crystalline state  $[d(N \rightarrow Si) \approx 301 pm]$ . The tetrasubstituted derivative (C6H4CH2NMe2)4Si (12) has no N  $\rightarrow$  Si contacts in solution and in the solid state: steric congestion does not allow higher coordination. CC 29-6 (Organometallic and Organometalloidal Compounds) Section cross-reference(s): 75 higher coordinated silicon compd; aminomethylphenyllithium reaction ST halosilane; nucleophilic substitution silicon center model; crystal mol structure aminomethylphenylsilane 27171-81-9, 2-(Dimethylaminomethyl)phenyllithium TT RL: RCT (Reactant); RACT (Reactant or reagent) (reaction of, with halosilanes) L76 ANSWER 21 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN ACCESSION NUMBER: 1989:135309 CAPLUS DOCUMENT NUMBER: 110:135309 TITLE: Silaheterocycles. III. Synthesis and reactivity of di-tert-butylneopentylsilaethene, tert-Bu2Si:CHCH2BuAUTHOR(S): Auner, N.

CORPORATE SOURCE: Anorg.-Chem. Inst., Westfael. Wilhelms Univ.,

Muenster, Fed. Rep. Ger.

SOURCE: Zeitschrift fuer Anorganische und Allgemeine Chemie

(1988), 558, 87-106

CODEN: ZAACAB; ISSN: 0044-2313

DOCUMENT TYPE: Journal LANGUAGE: German

OTHER SOURCE(S): CASREACT 110:135309

AB Vinylation of (Me3C)2SiXX1 (X = H, X1 = Cl, X = X1 = Cl, F) with H2C:CHLi gave (Me3C)2Si(X)CH:CH2 (I). In the treatment of I with Me3CLi, the first step is the generation of the α-lithio compound (Me3C)2Si(X)CH(Li)CH2CMe3; the following reaction is governed by the nature of the substituent and the reaction conditions (solvent, concentration, temperature). For X = H, 2,3-LiH elimination leads to (Me3C)2Si(H)CH:CH2CMe3 (II); with X = F, Cl, Si:C formation by 1,2-LiX elimination competes with intermol. Si-C coupling to produce (Me3C)2Si(H)CH{Si(CMe3)2CH:CHCMe3}CH2CM e3 as the main product. Mechanism of the formation of the products are discussed.

CC 29-6 (Organometallic and Organometalloidal Compounds)

IT 917-57-7, Vinyllithium

RL: RCT (Reactant); RACT (Reactant or reagent)
 (vinylation by, of halosilanes)

L76 ANSWER 22 OF 22 CAPLUS COPYRIGHT 2006 ACS on STN

ACCESSION NUMBER: 1986:424331 CAPLUS

DOCUMENT NUMBER: 105:24331

TITLE: The (p-d)  $\pi$  bonding in fluorosilanes? Gas-phase

structures of (CH3)4-nSiFn with n = 1-3 and of

(tert-Bu)2SiF2

AUTHOR(S): Rempfer, Beate; Oberhammer, Heinz; Auner,

Norbert

CORPORATE SOURCE: Inst. Phys. Theor. Chem., Univ. Tuebingen, Tuebingen,

7400, Fed. Rep. Ger.

SOURCE: Journal of the American Chemical Society (1986),

108(14), 3893-7

CODEN: JACSAT; ISSN: 0002-7863

DOCUMENT TYPE: Journal LANGUAGE: English

OTHER SOURCE(S): CASREACT 105:24331

AB Gas-phase structures (rg) of the methylfluorosilanes Me4-nSiFn (n = 1-3) and of di-tert-butyldifluorosilane have been determined by electron diffraction. In the case of MeSiF3 the **microwave** rotational constant was included in the structure anal. In the methylfluorosilane series a steady decrease of Si-F and Si-C bond lengths is observed with increasing fluorination. These trends are rationalized by increasing polar contributions and contraction of the Si valence shell. Ab initio calcns. for SiF4 indicate that (p-d)  $\pi$  bonding is negligible. Substitution of the Me groups in Me2SiF2 by Me3C groups leads to lengthening of Si-F and Si-C bonds and strong variations in the Si bond angles.

CC 29-6 (Organometallic and Organometalloidal Compounds) Section cross-reference(s): 22 This Page Blank (uspto)